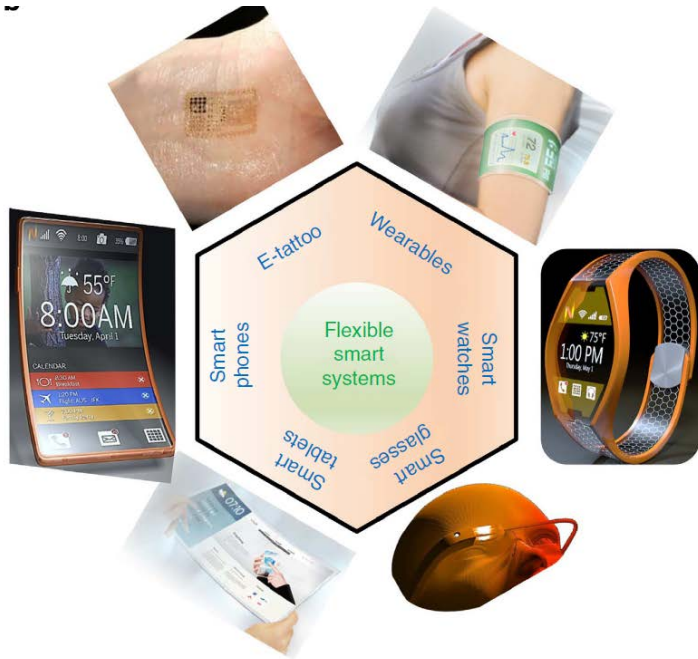
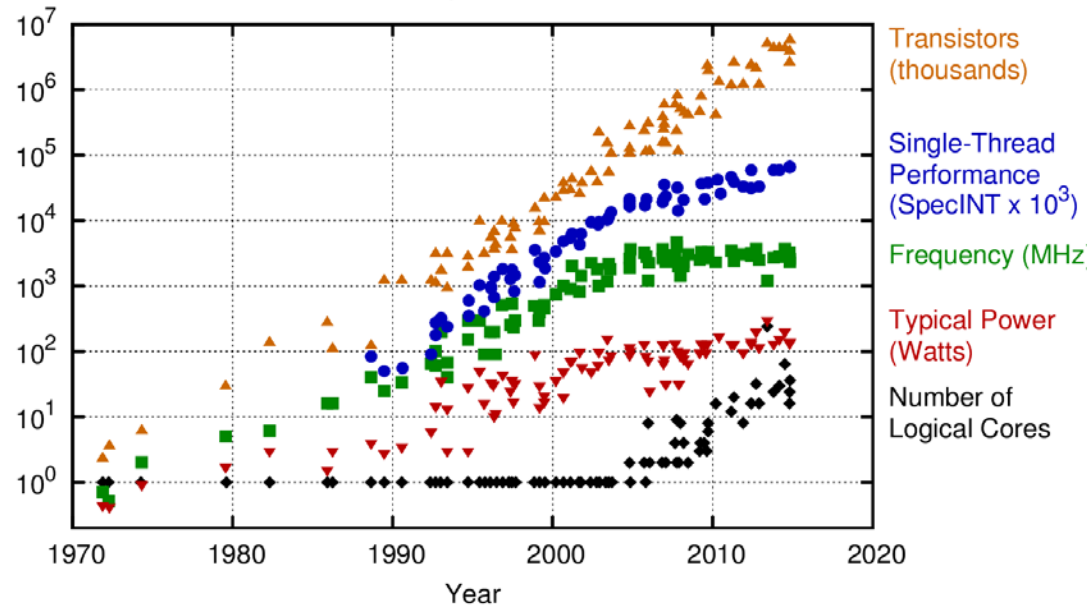


Electronics in Flatland

H.Movva, A.Sanne, A.Rai, O.Mohammed, A.Roy, S.Majumder,
D.Akinwande, E.Tutuc, L.F.Register
and S.K. Banerjee
University of Texas at Austin



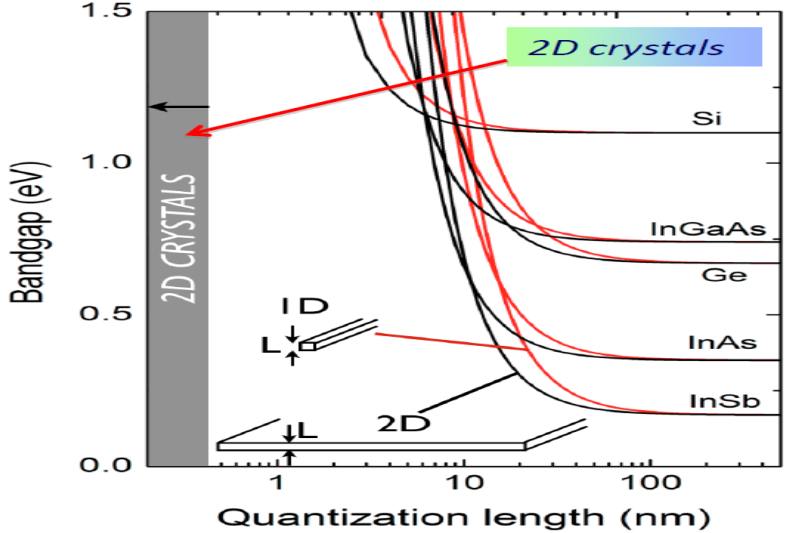
40 Years of Microprocessor Trend Data



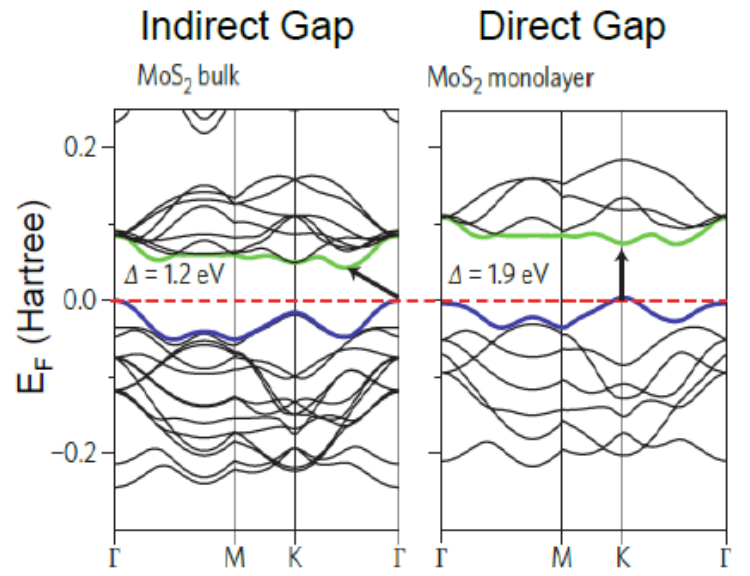
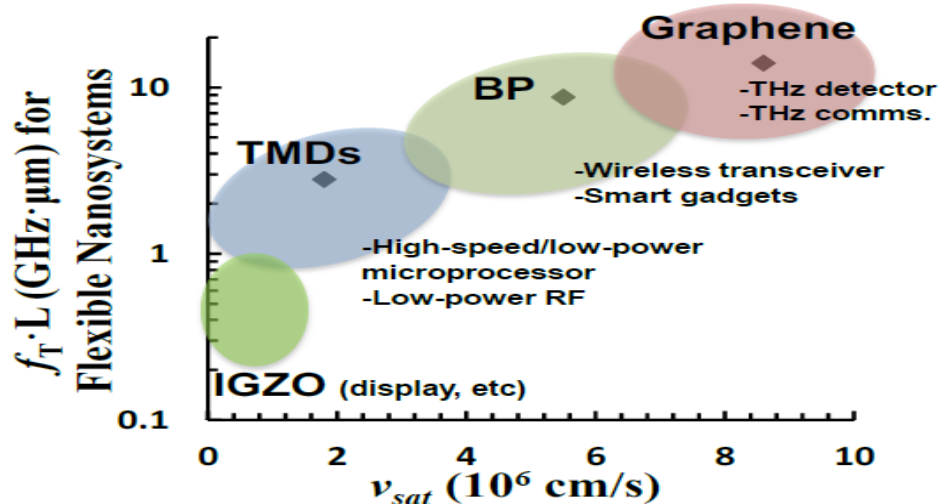
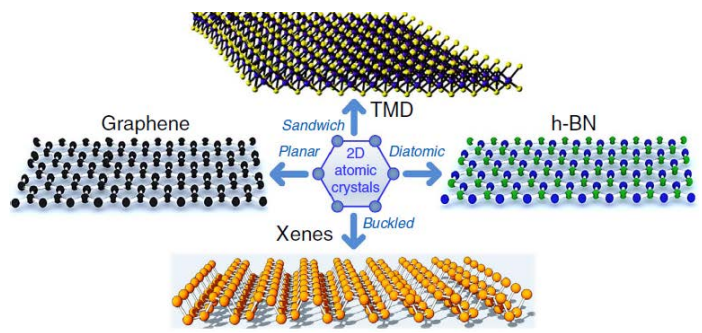
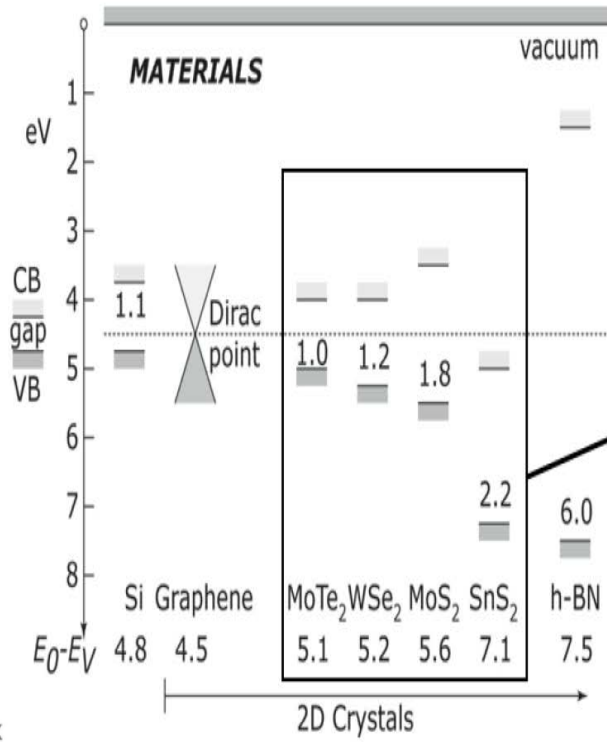
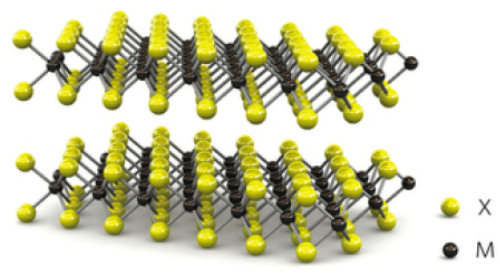
Original data up to the year 2010 collected and plotted by M. Horowitz, F. Labonte, O. Shacham, K. Olukotun, L. Hammond, and C. Batten
New plot and data collected for 2010-2015 by K. Rupp

- Medium Frequency, Low Power IoT Devices
- Beyond-CMOS Low Power Transistors

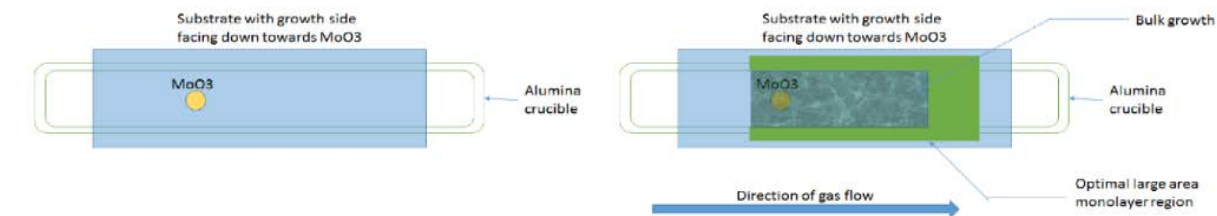
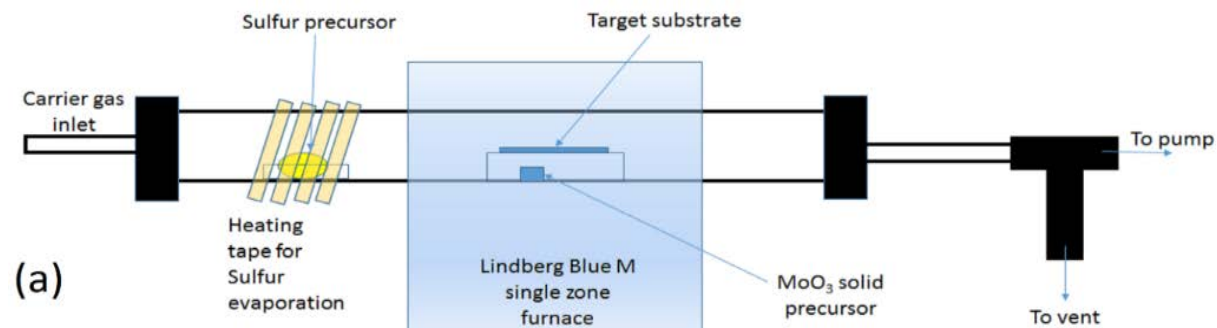
Acknowledgments: NRI SWAN, NSF NASCENT ERC, NNCI, DOE BAPVC, Army STTR



Mo [Kr]4d⁵5s
S [Ne]3s²3p⁴

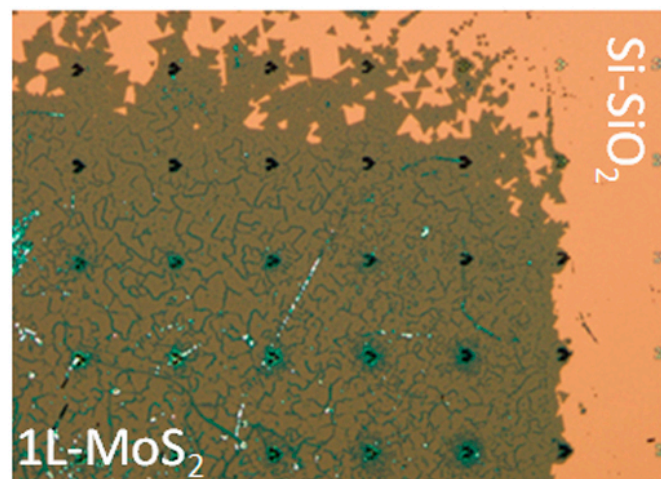
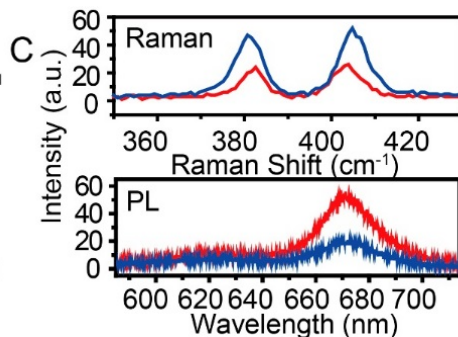
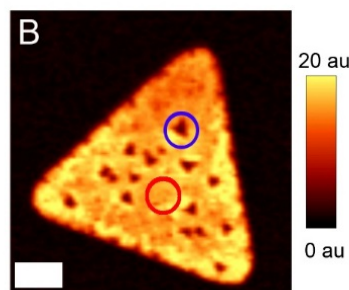
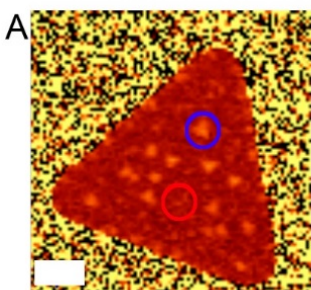
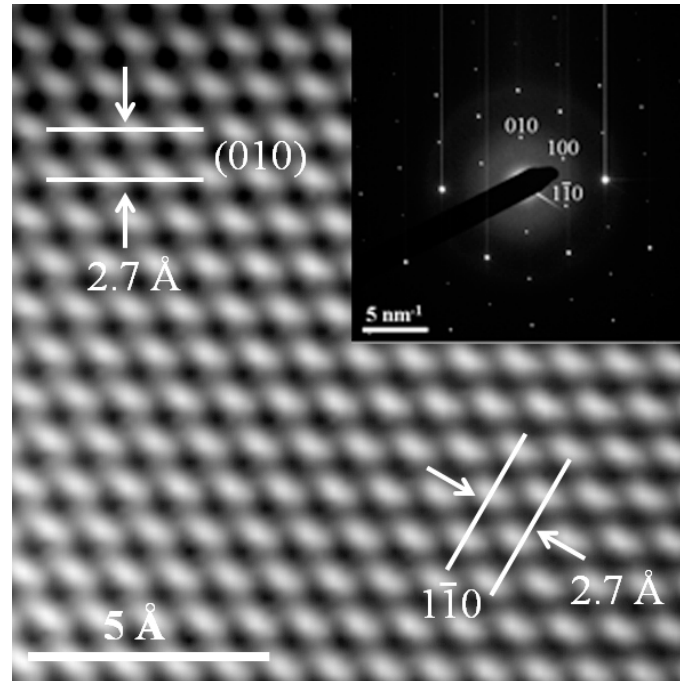


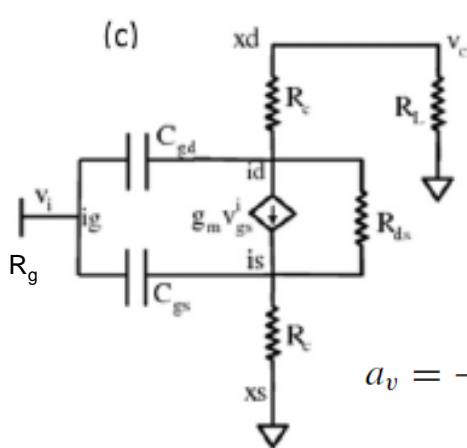
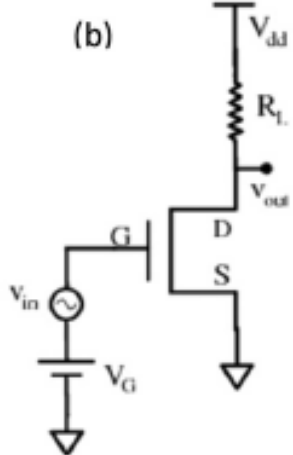
MoS₂ CVD growth chamber with solid precursors



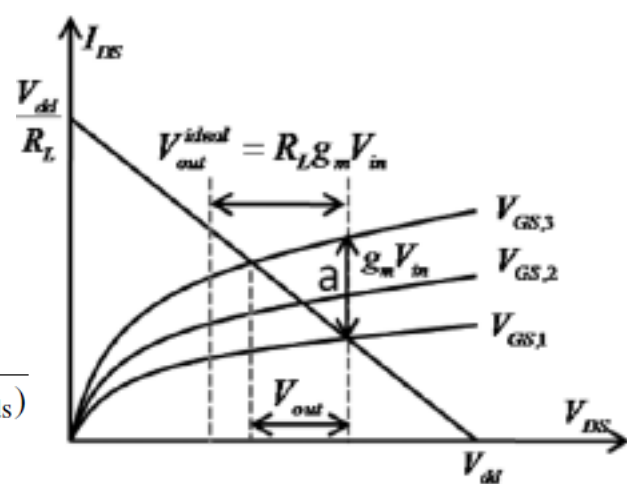
(b) before growth

(c) after growth



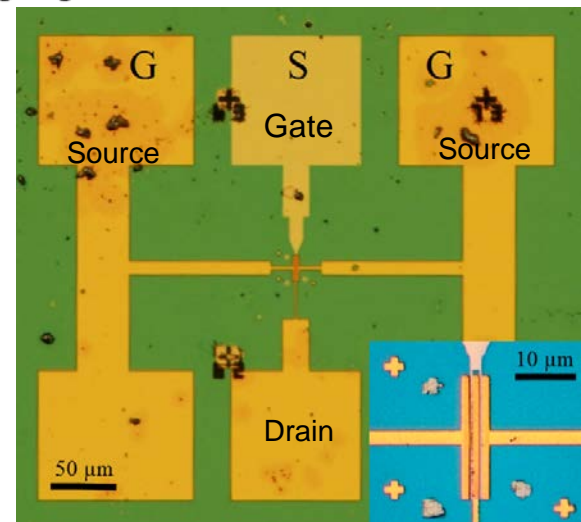
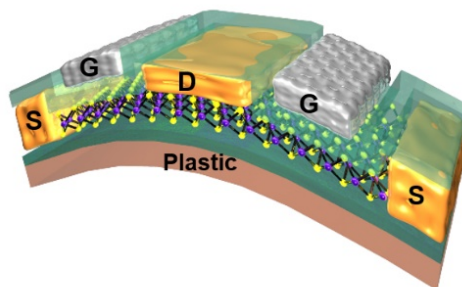
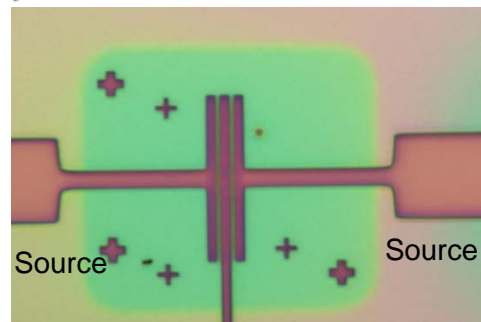
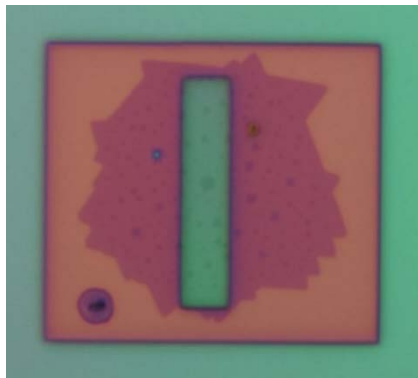
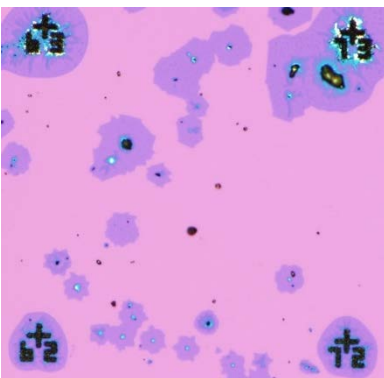


$$a_v = - \frac{R_L g_m R_{ds}}{R_L + R_{ds} + R_c (2 + g_m R_{ds})}$$

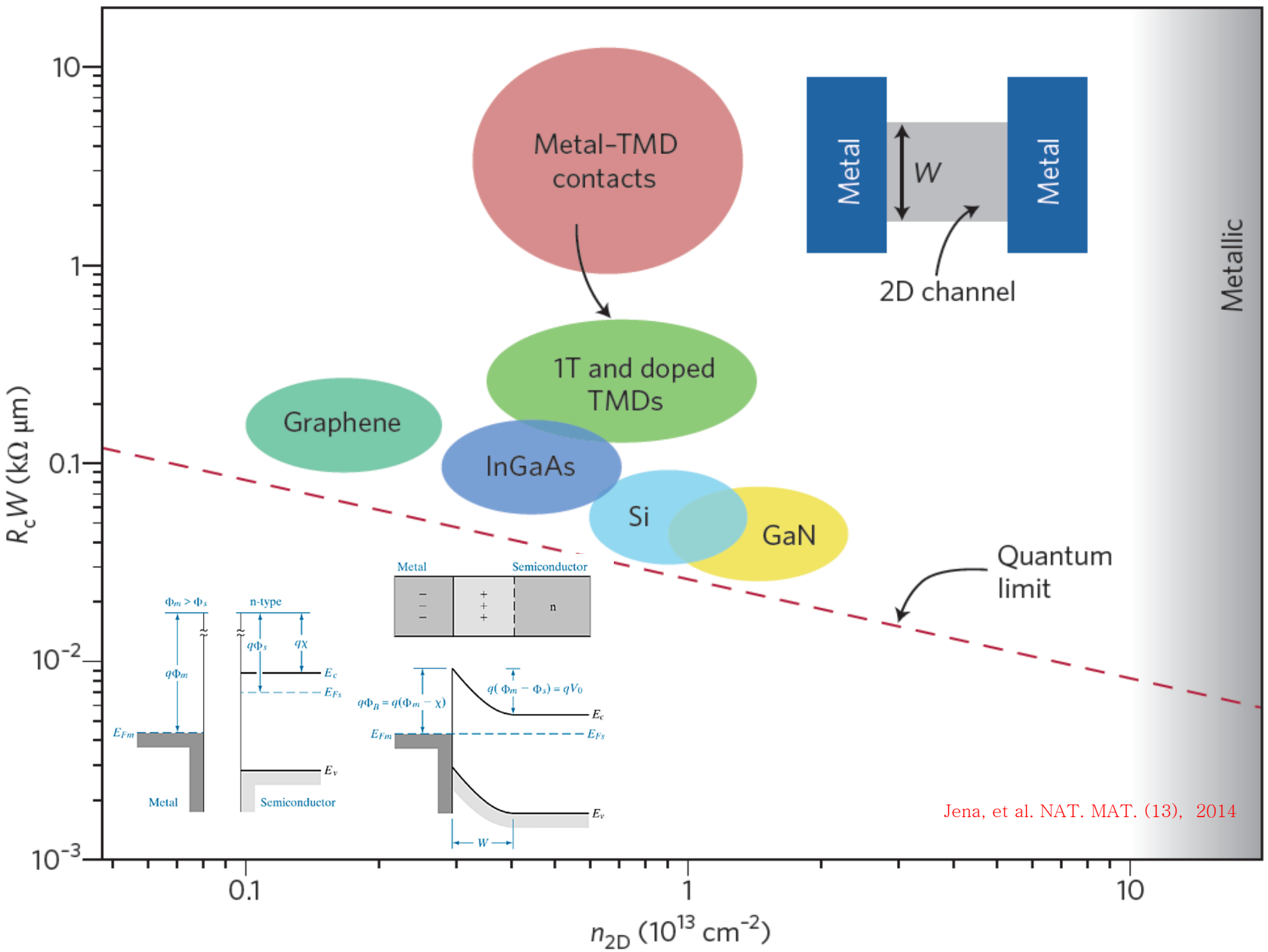


Unity current gain at $f_T = \frac{g_m}{2\pi(C_{gs} + C_{p,gs} + C_{p,gd})((R_{c,s} + R_{c,d})g_{ds} + 1) + C_{p,gd}g_m(R_{c,s} + R_{c,d})} = g_m / 2\pi C_{gs} = 1 / 2\pi\tau$

Unity Power gain at $f_{max} = \frac{f_T}{\sqrt{2g_{ds}(R_{c,s} + R_{gate}) + 2\pi f_T C_{p,gd} R_g}}$



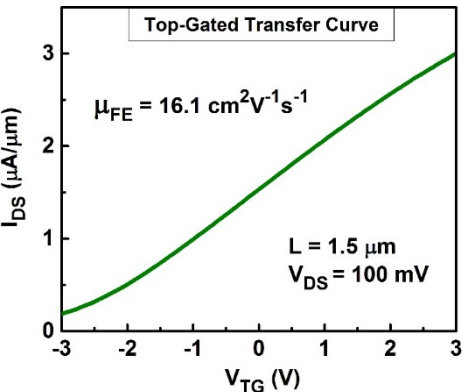
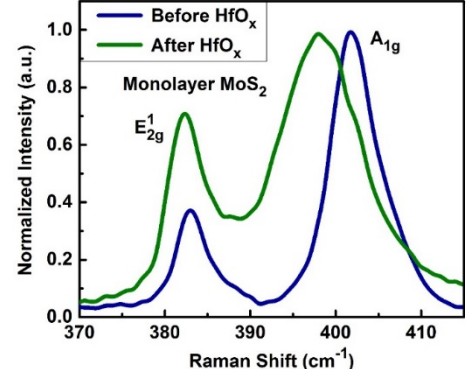
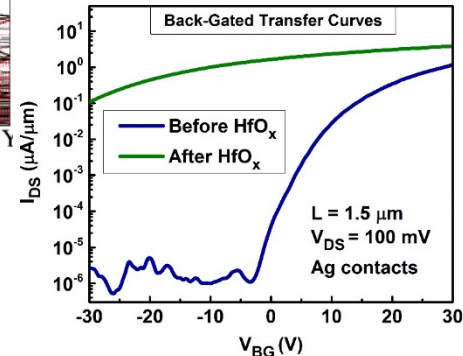
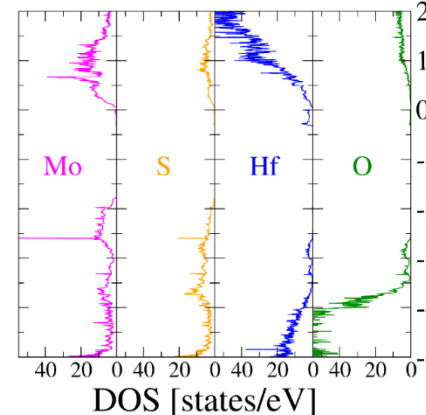
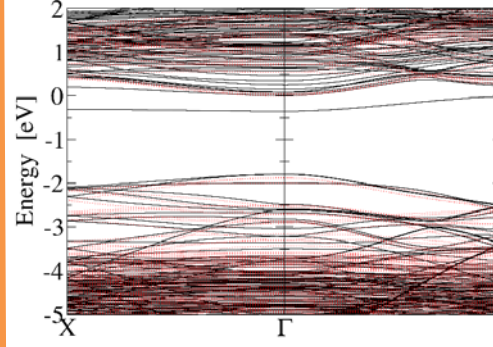
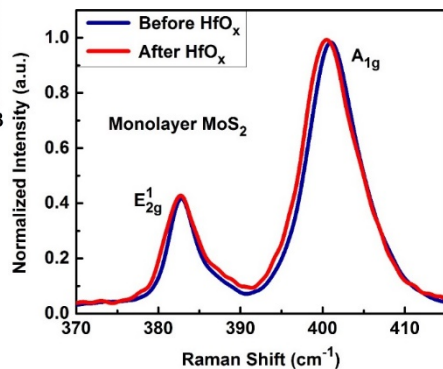
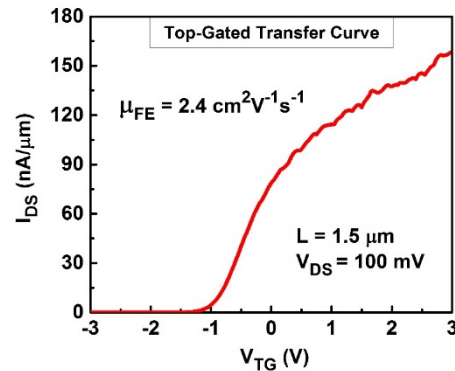
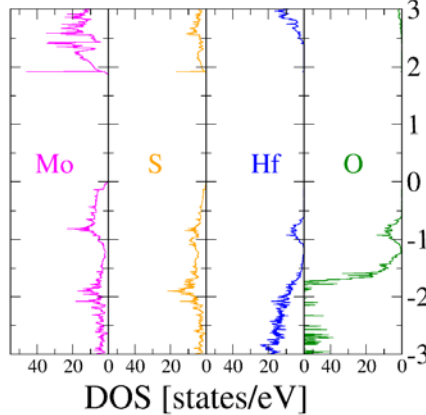
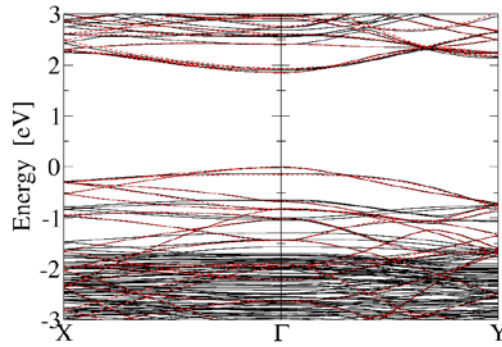
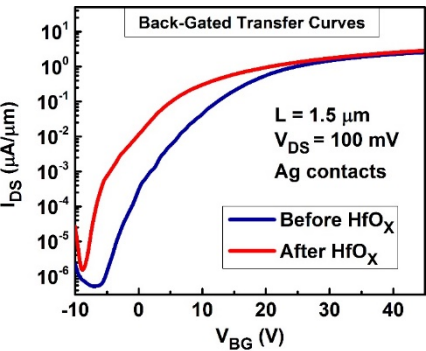
- 1) Active area
- 2) S/D contacts
- 3) Top gate



MoS₂ on ALD HfO₂

Without O-vacancy: HfO₂

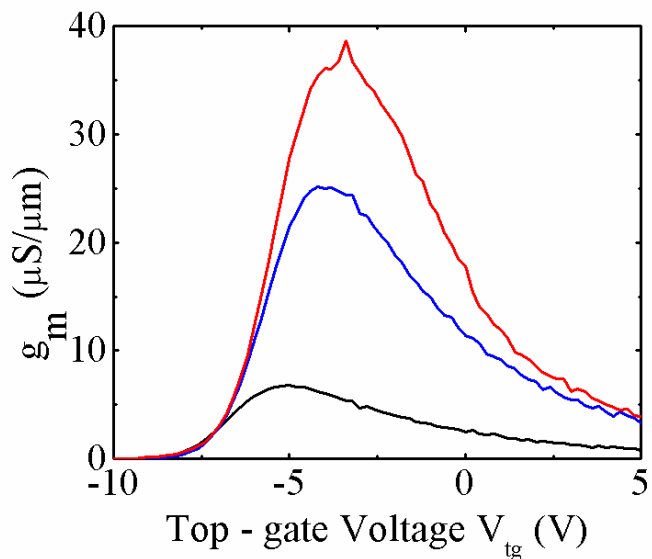
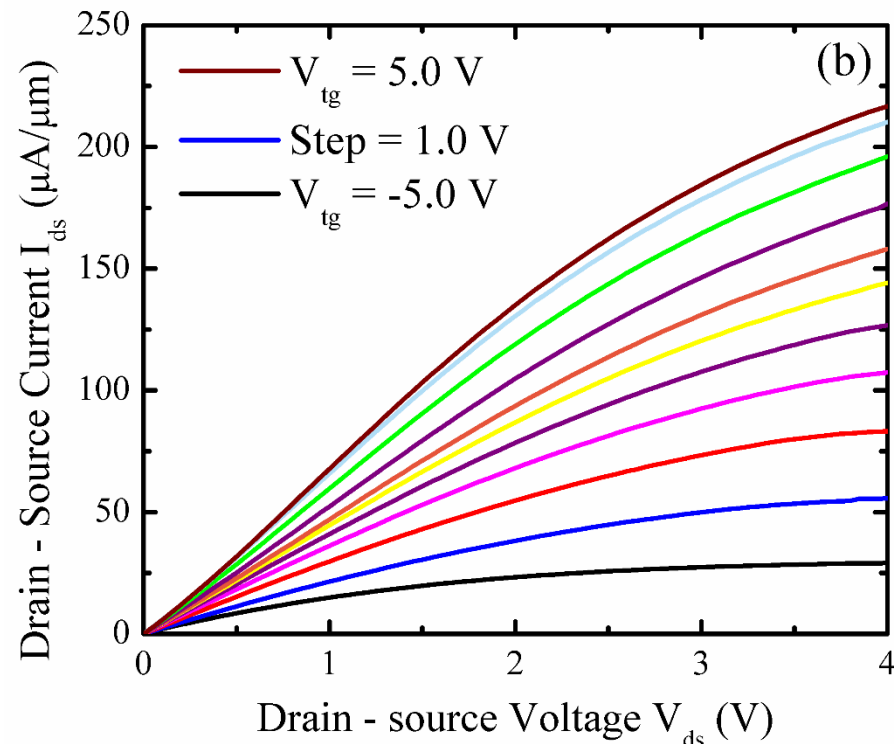
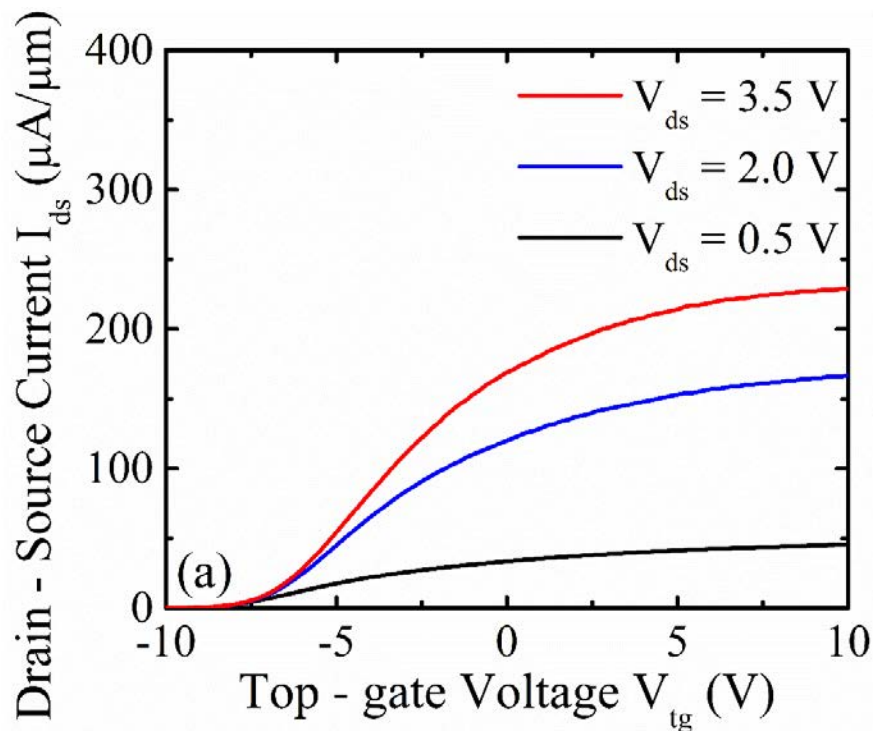
With O-vacancy: HfO_{1.6}



Similar results for Hf-termination and H-passivation, and other high-k (Al₂O₃, TiO₂)

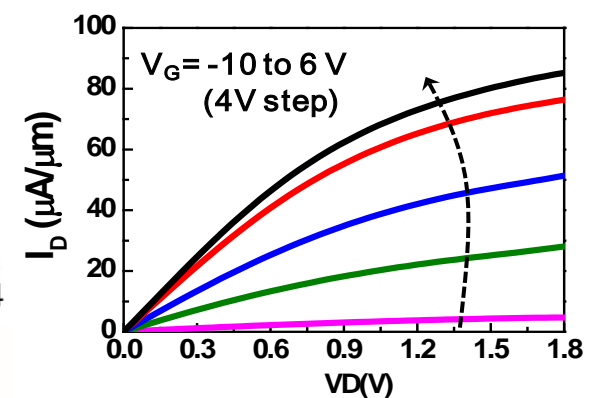
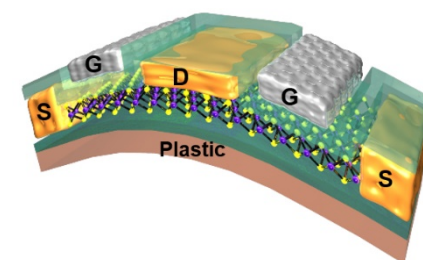
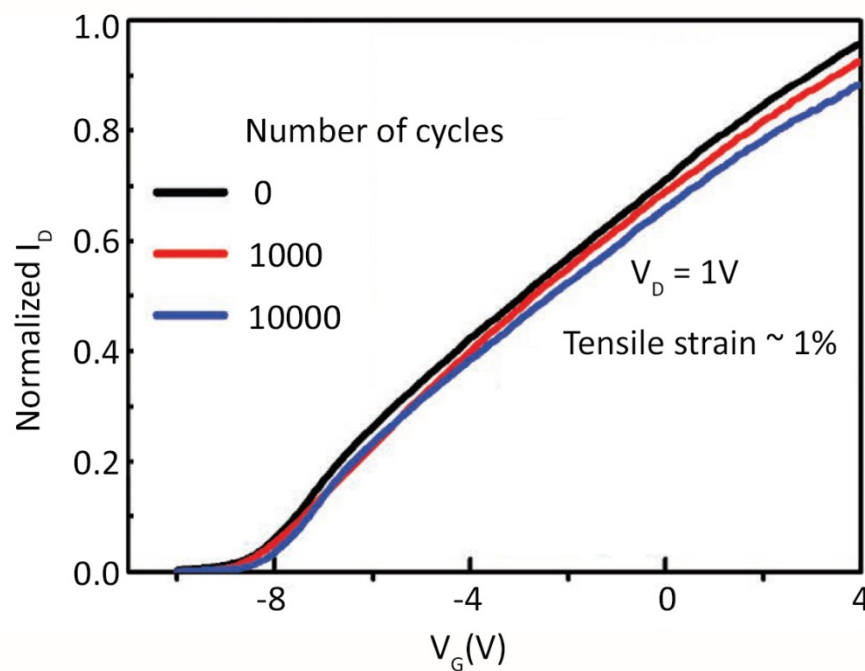
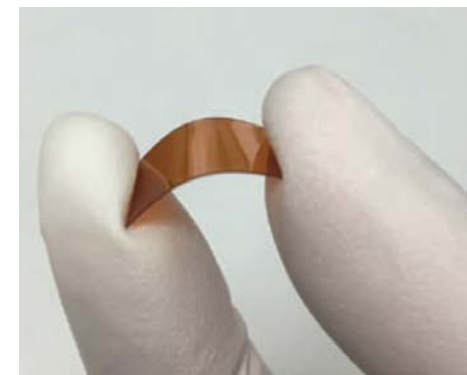
Rai, Valsraj... Register, Tutuc, Banerjee, Nanoletters (2015)

Top Gated MoS₂ DC Characteristics

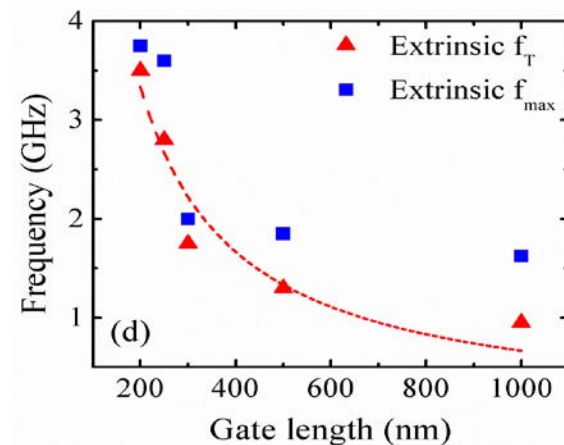
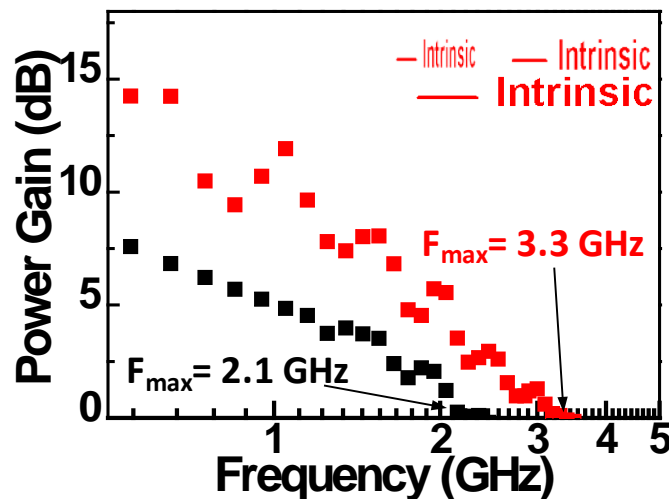
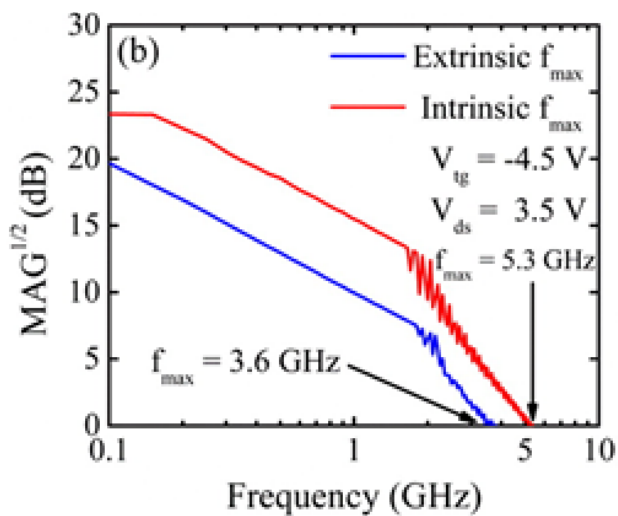
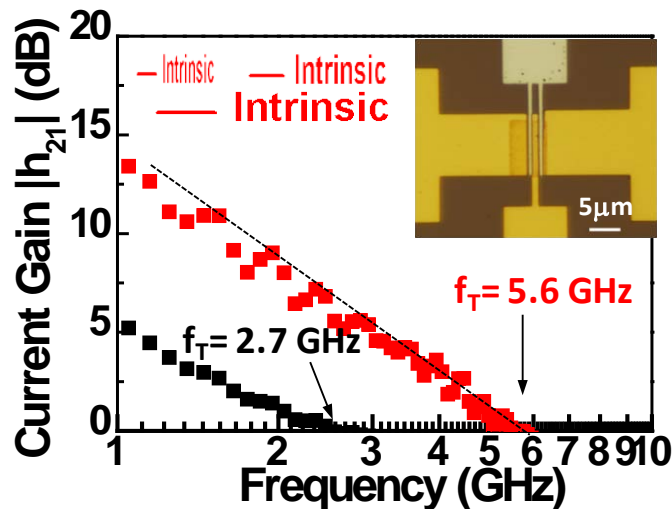
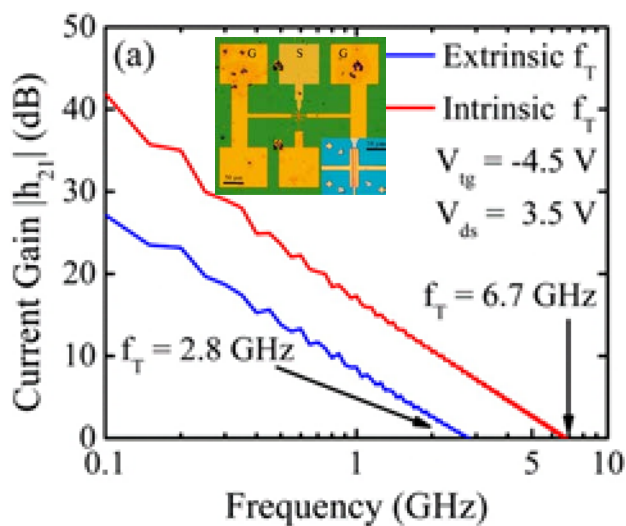


- Monolayer CVD MoS₂ on 285 nm SiO₂ on Si; L= 250 nm
- 30 nm ALD HfO_{1.56}; Ni gate (50 nm); $V_T = -9\text{V}$
- 20 nm Ag/30 nm Au S/D contacts
Schottky barrier = 0.07 eV; $R_{\text{contact}} = 2\text{k}\Omega\text{-}\mu\text{m}$
- Highest peak g_m (at $V_{tg} = -4.5\text{V}$, $V_{ds} = 3.5\text{V}$) = $38\ \mu\text{S}/\mu\text{m}$
& mobility = $63\ \text{cm}^2/\text{Vs}$ for CVD MoS₂; $V_{\text{sat}} = 10^6\ \text{cm/s}$

MoS₂ FET fabrication and characterization on flexible polyimide substrates

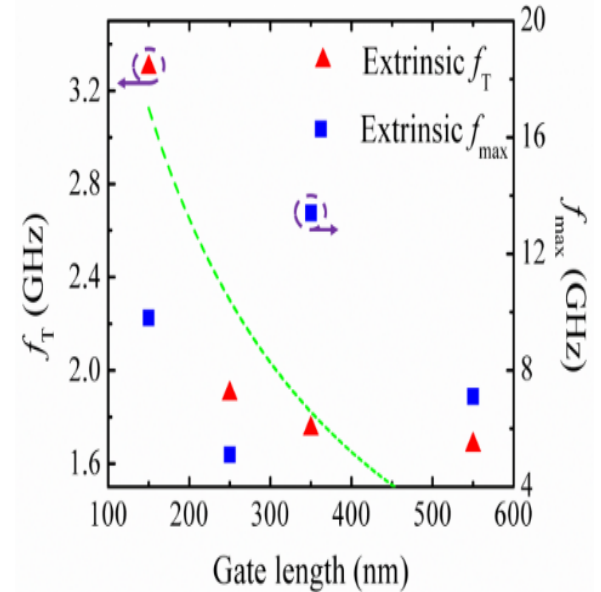
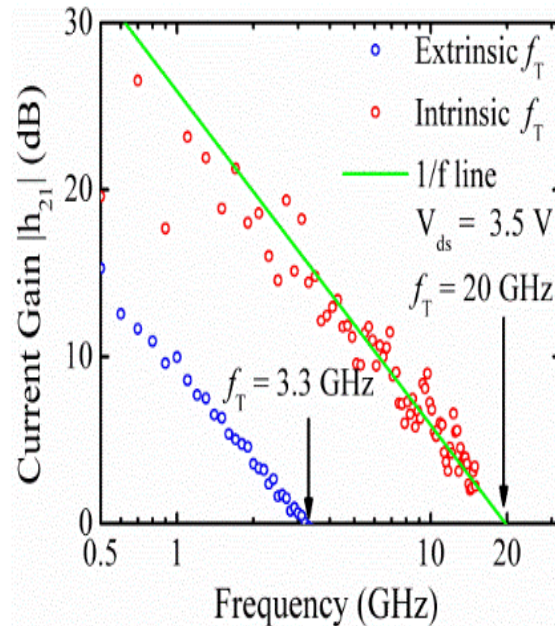
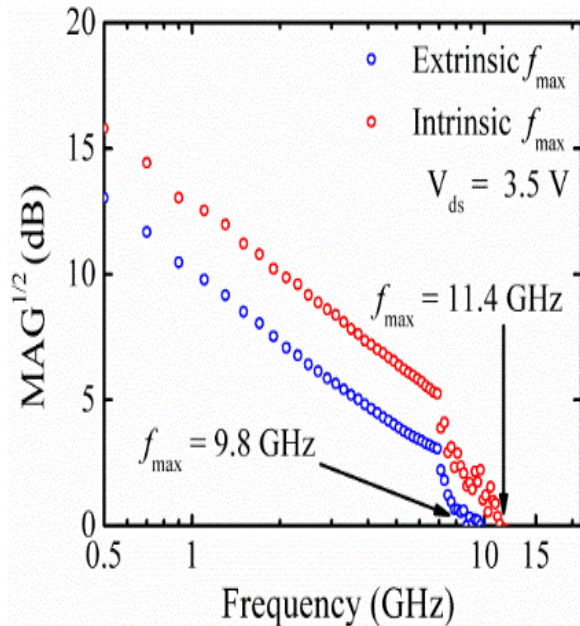
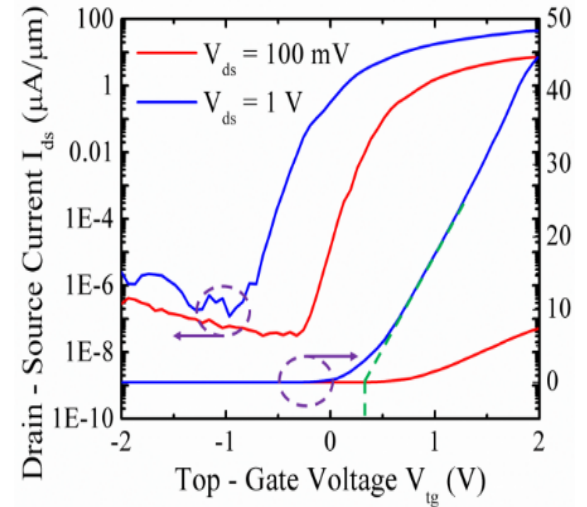
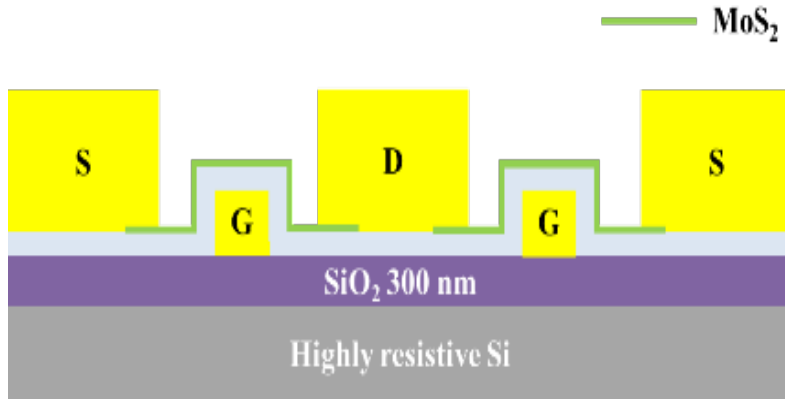


High Frequency Performance of MoS₂ Flexible RF FETs

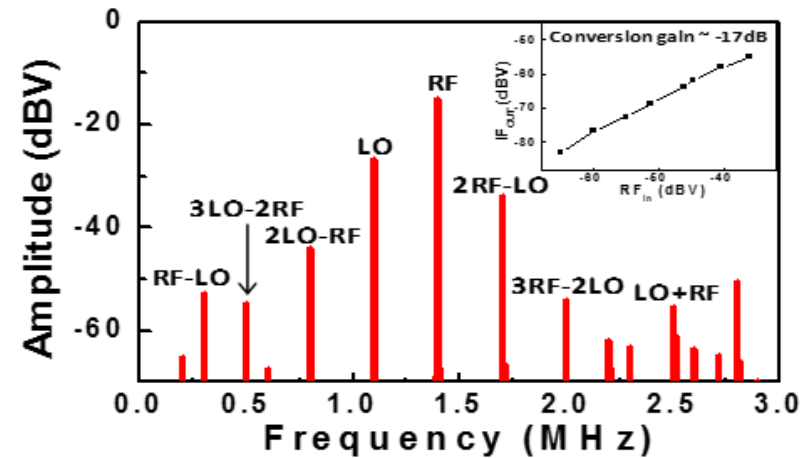
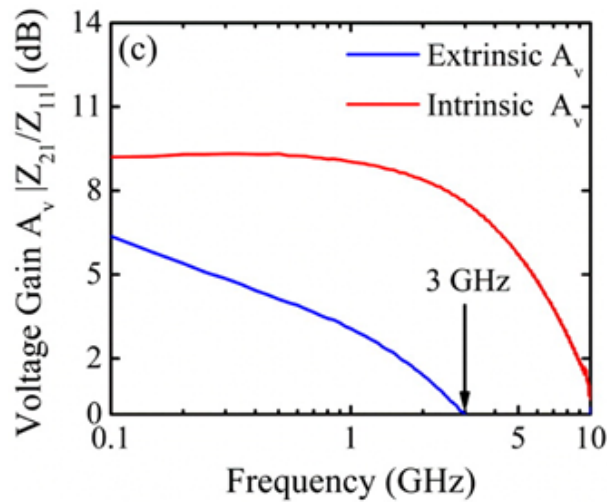
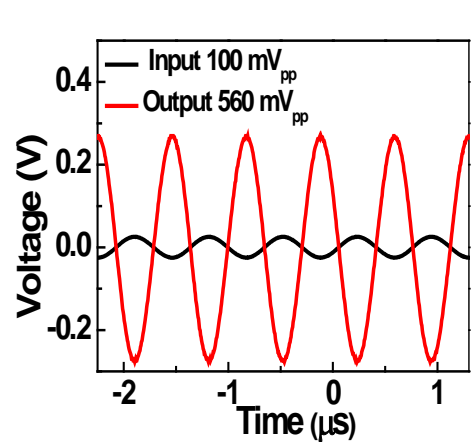
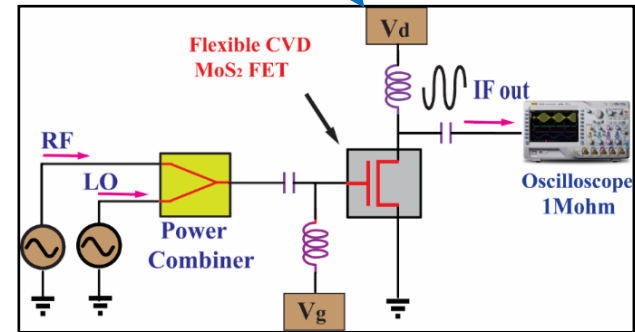
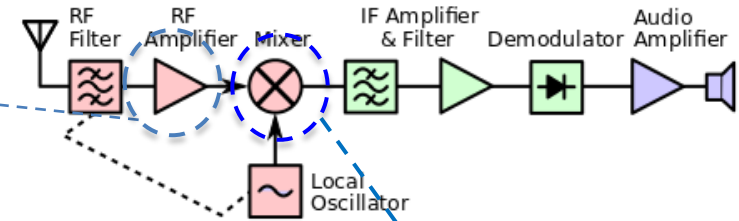
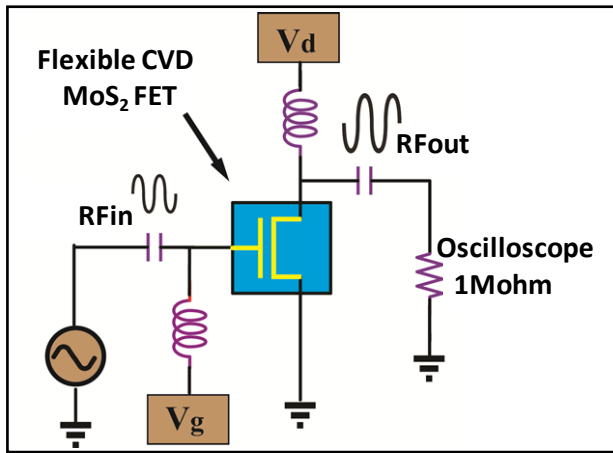


- MoS₂ RF Transistor on SiO₂/Si
- MoS₂ RF Transistor on Polyimide

Back-gated CVD MoS₂ FETs



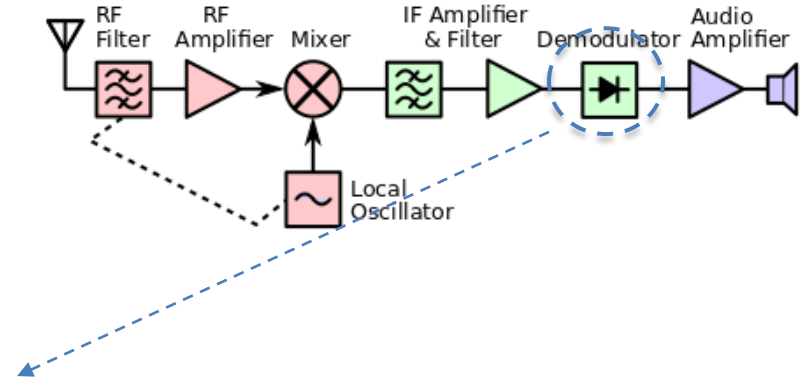
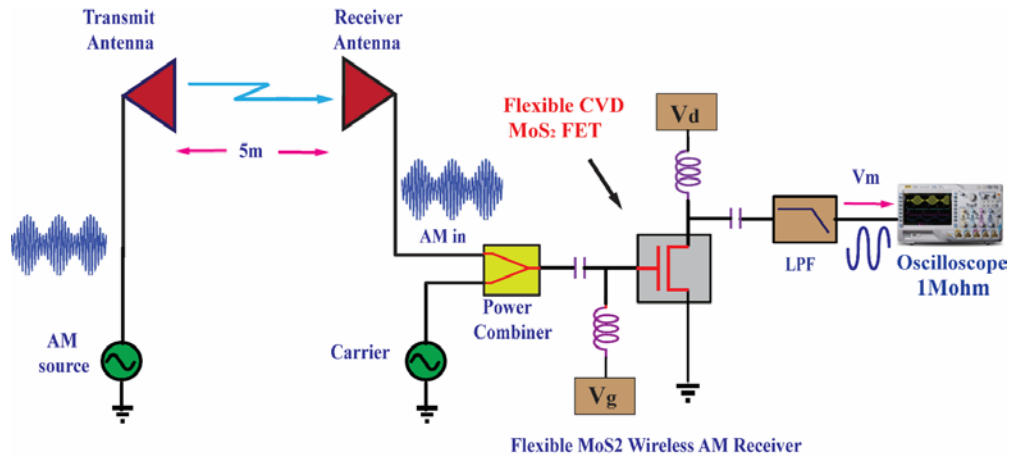
Flexible MoS₂ based RF circuits



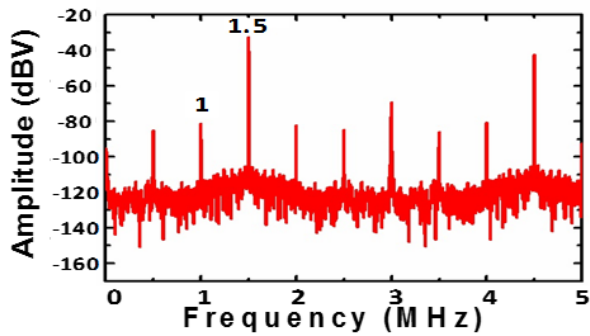
Flexible MoS₂ amplifier

Flexible MoS₂ Mixer

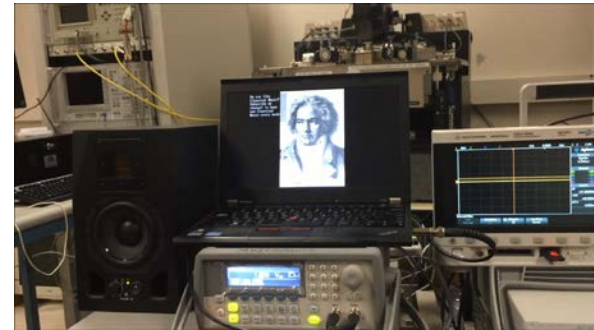
Flexible MoS₂ based Radio



Flexible MoS₂ AM Demodulator

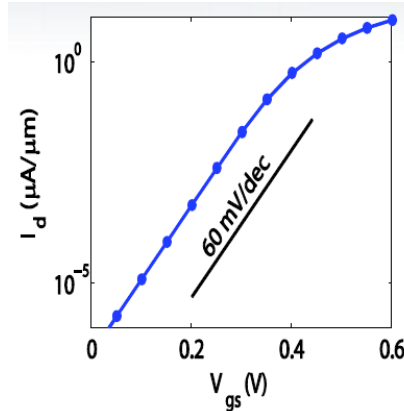
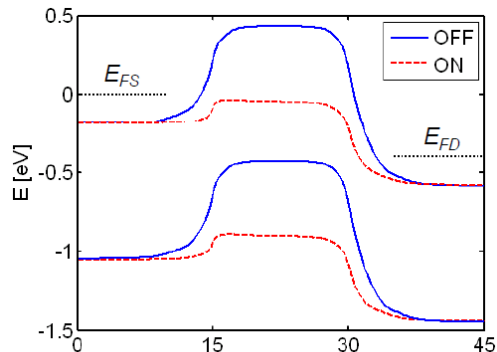
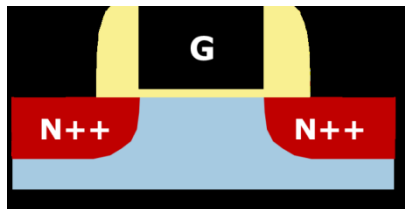


- Flexible MoS₂ AM Receiver Output Spectrum



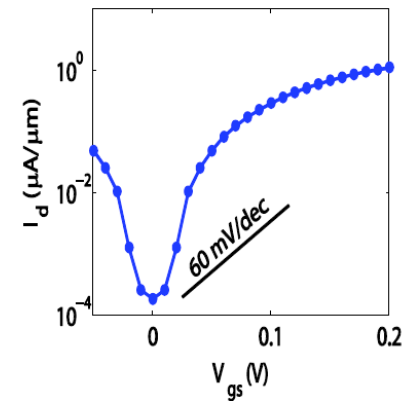
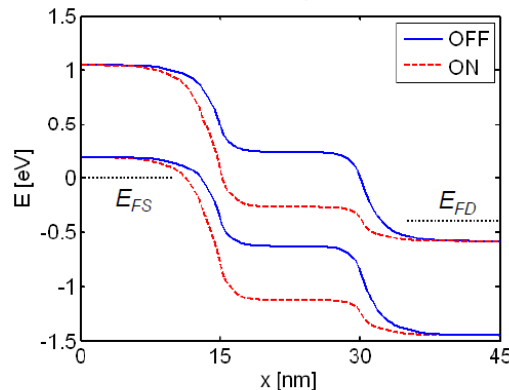
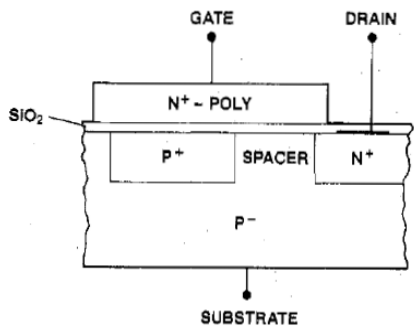
MOSFETs vs. Steep Slope TFETs & Resonant TFETs

MOSFETs

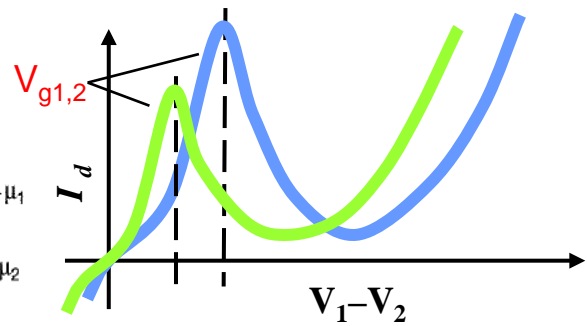
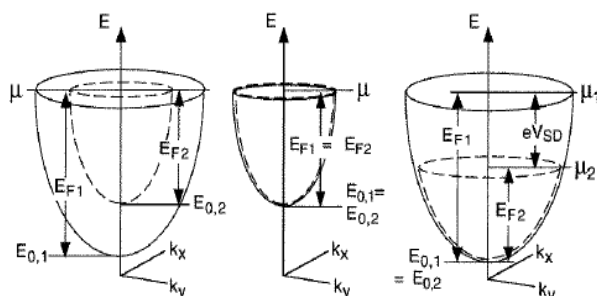
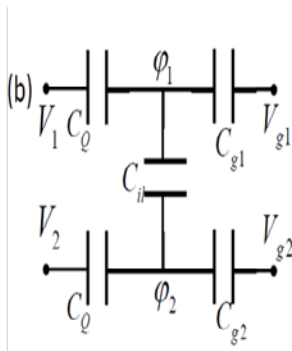
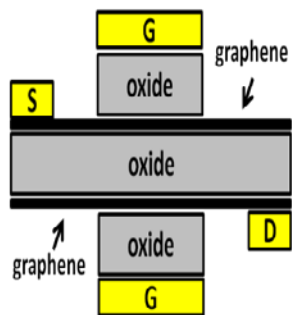


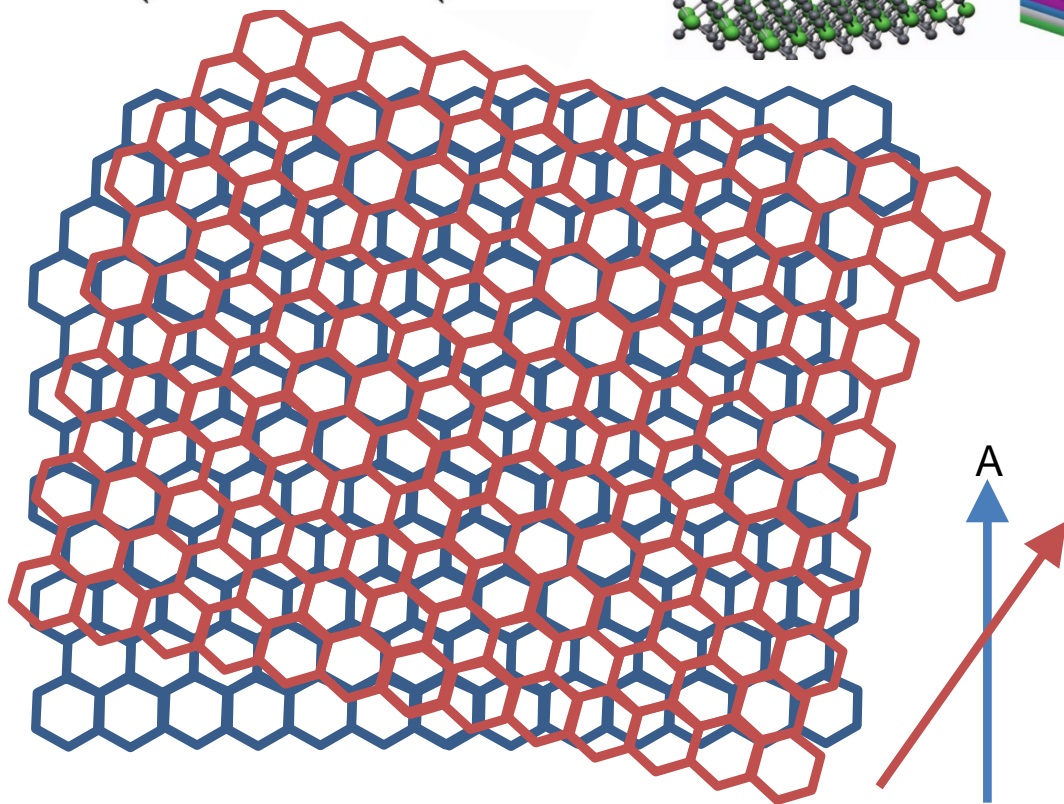
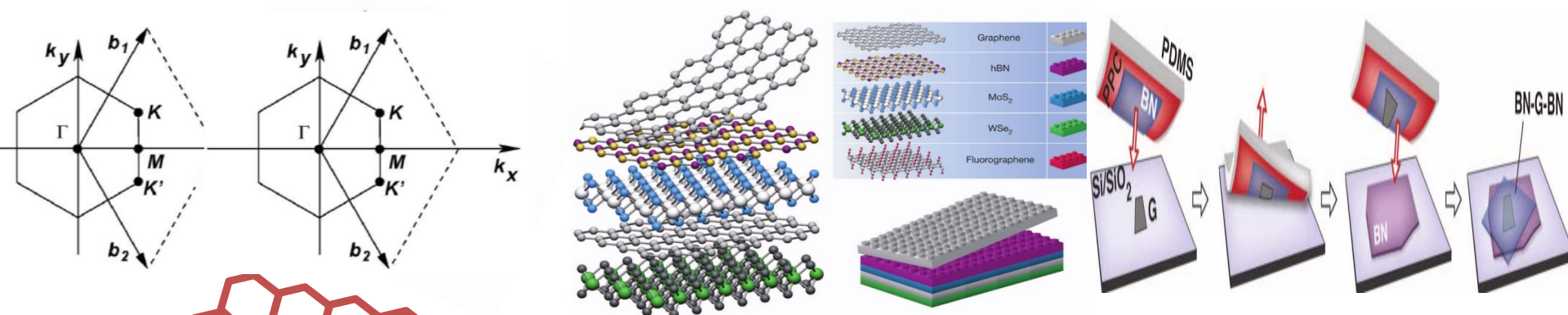
Steep slope TFETs

(Banerjee, ..EDL 1987)

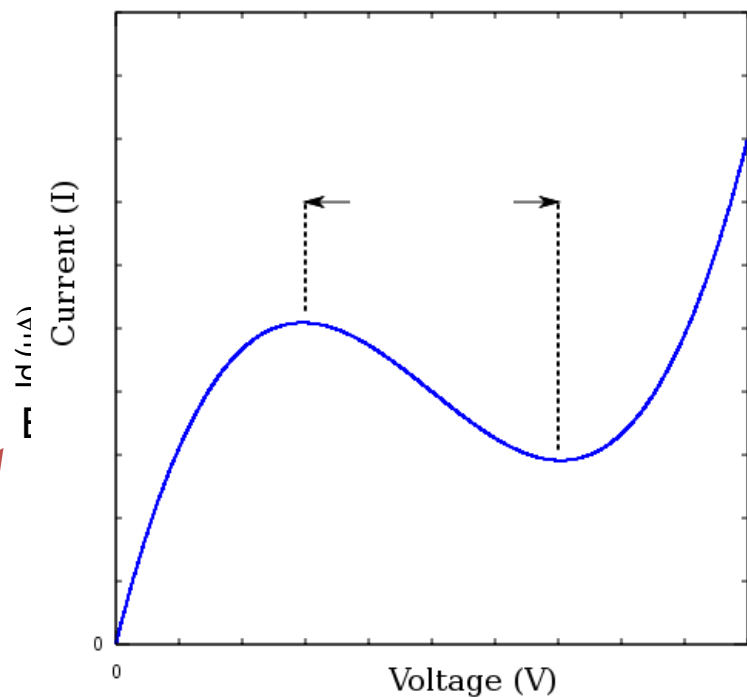


Resonant ITFETs



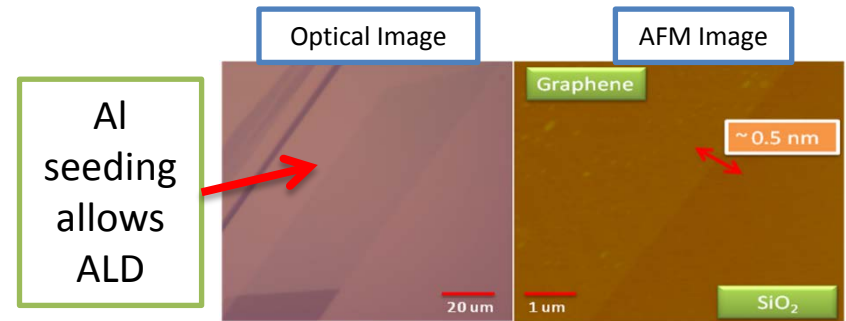
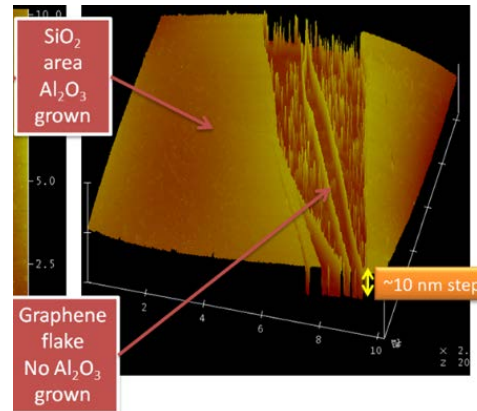
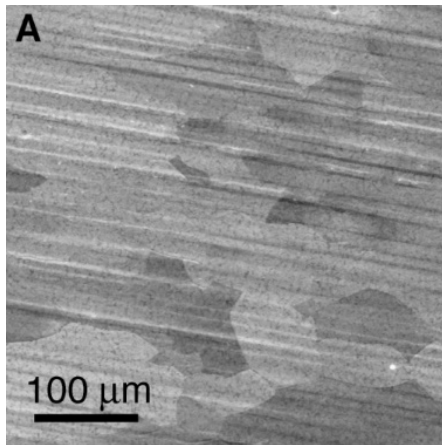
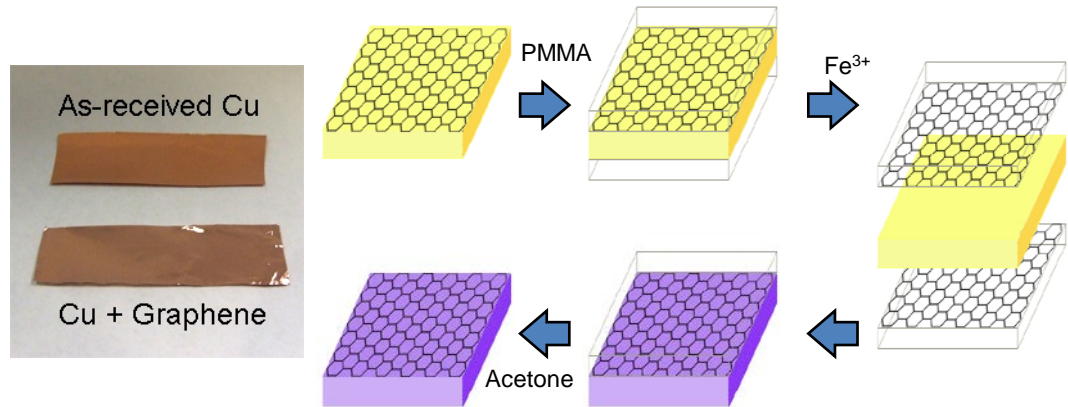
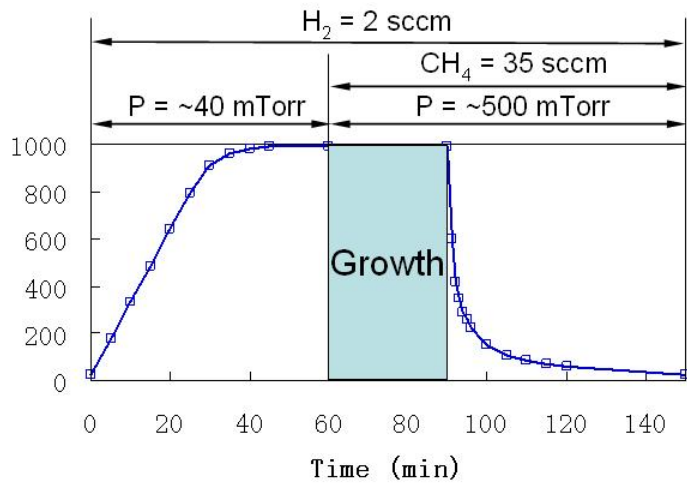


Rotationally Aligned 2D materials



Negative differential resistance

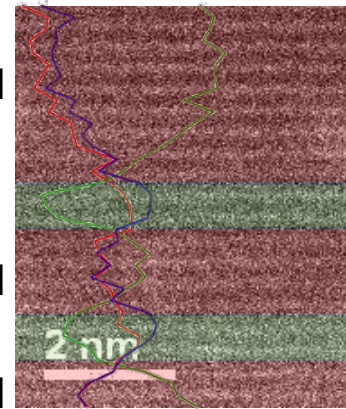
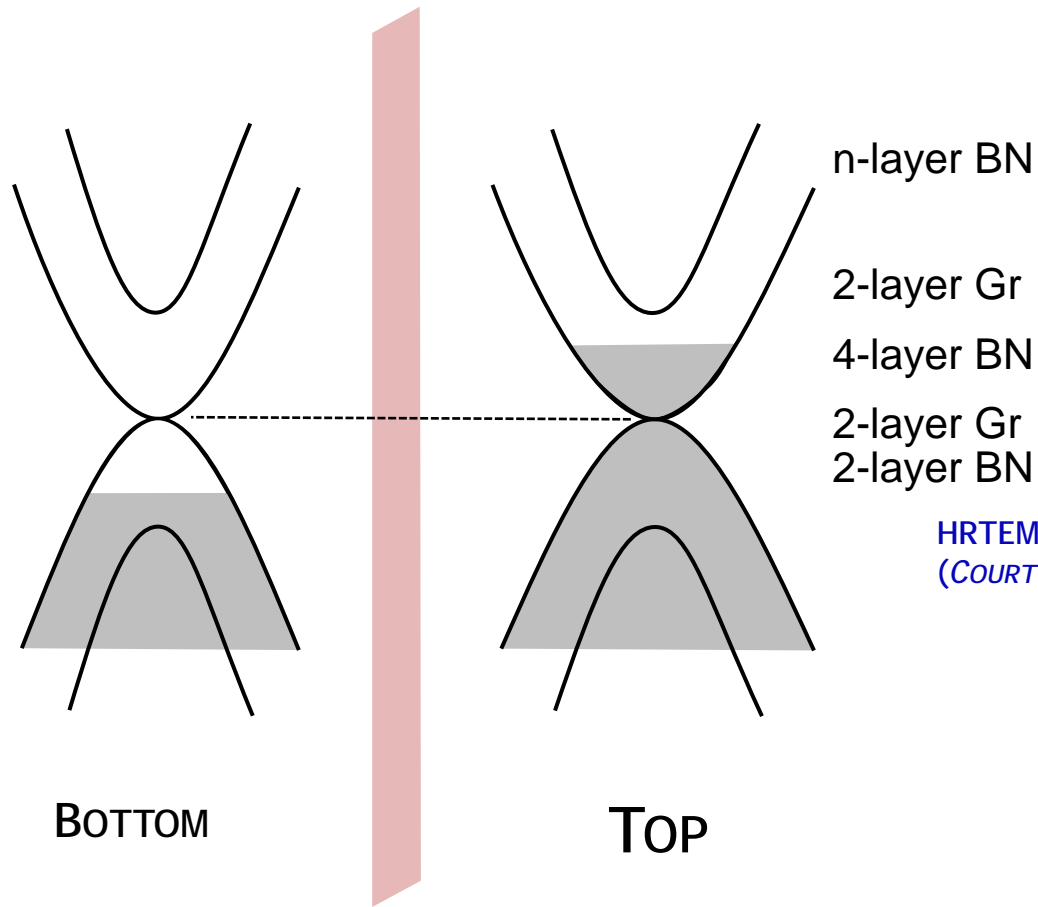
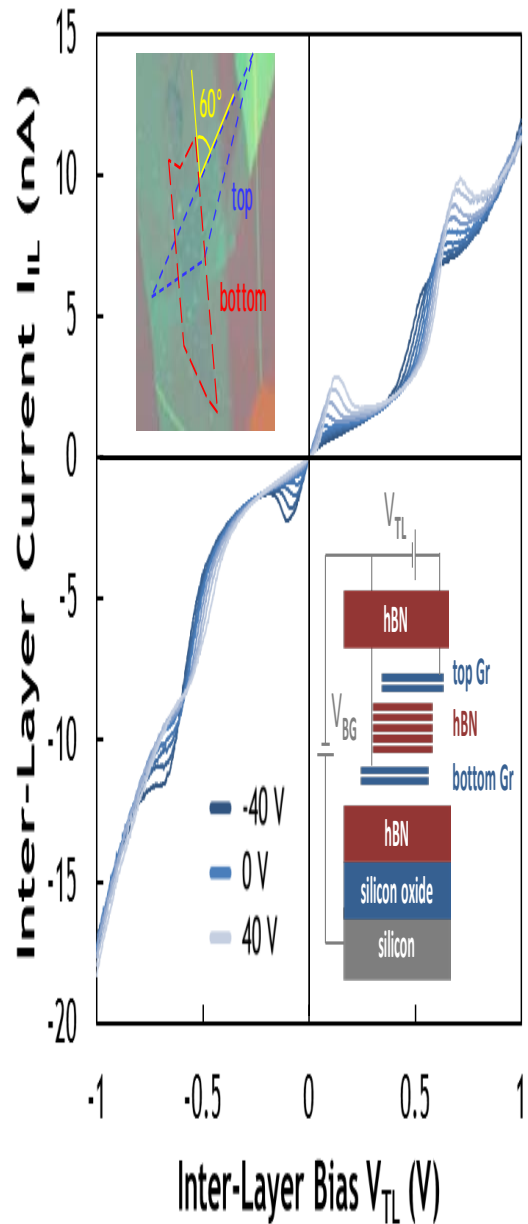
Large-Area Graphene Grown on Cu Foils and FETs with high-k



Large-Area Synthesis of High-Quality and Uniform Graphene Films on Copper Foils

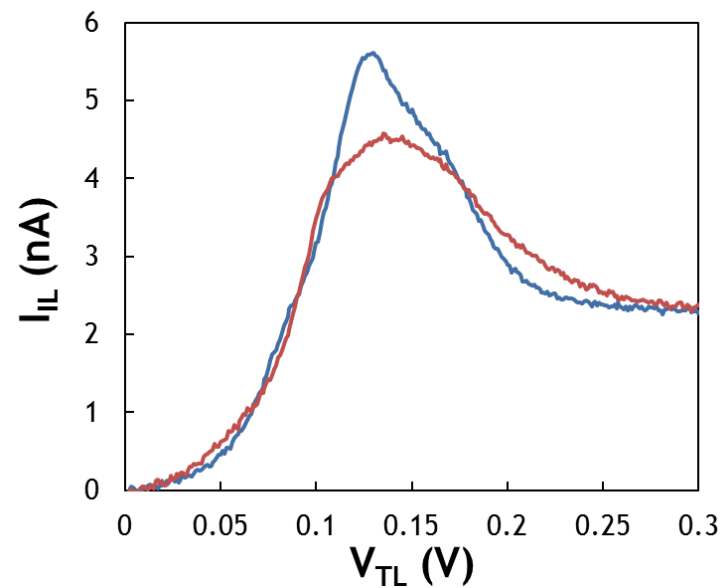
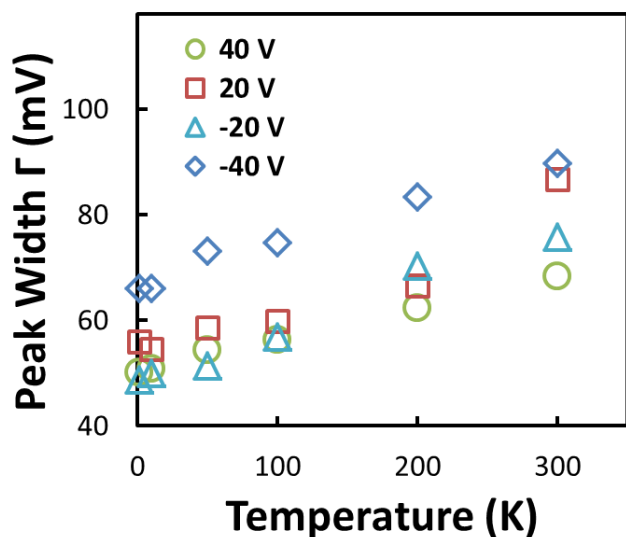
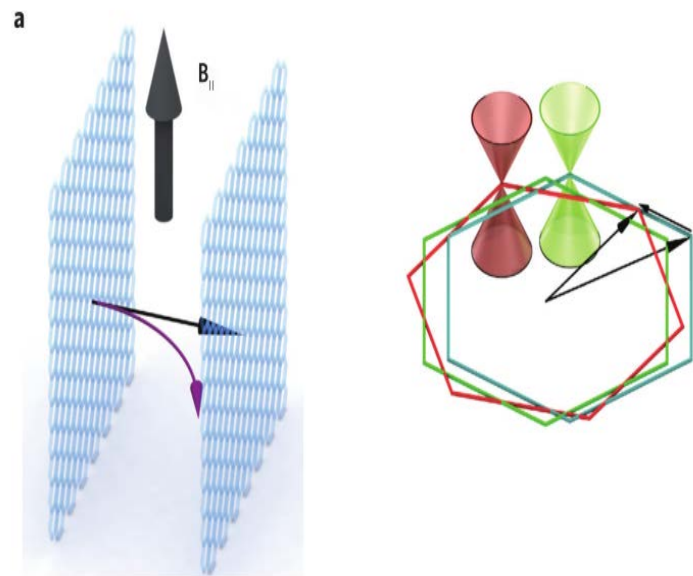
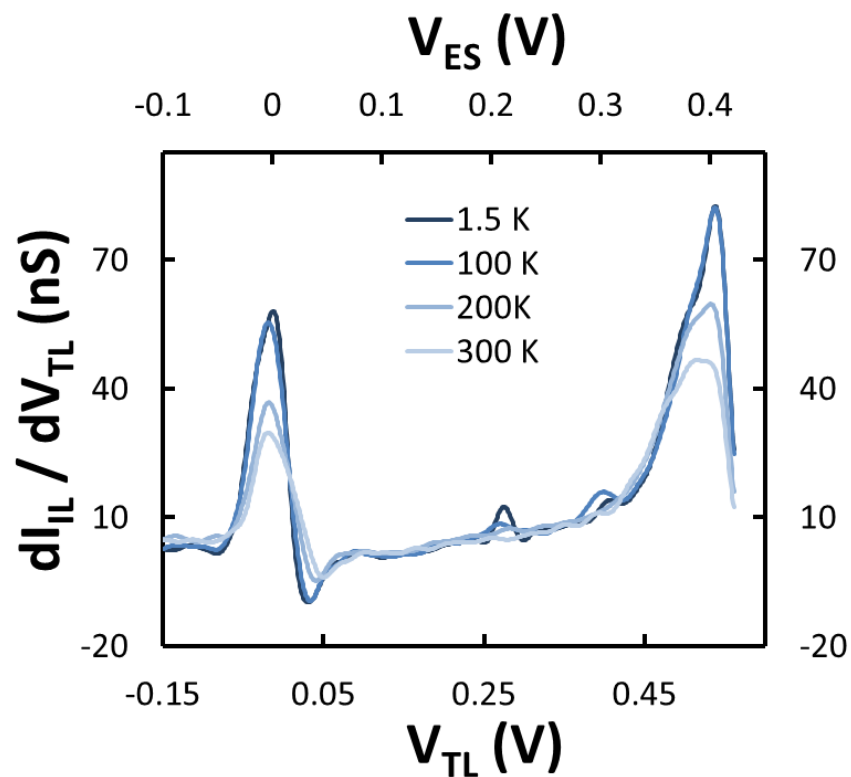
Xuesong Li, Weiwei Cai, Jinho An, Seyoung Kim, Junghyo Nah, Dongxing Yang, Richard Piner, Aruna Velamakanni, Inhwa Jung, Emanuel Tutuc, Sanjay K. Banerjee, Luigi Colombo, Rodney S. Ruoff. *Science*, 2009 (6500 citations)

Origin of the First and Second NDR?

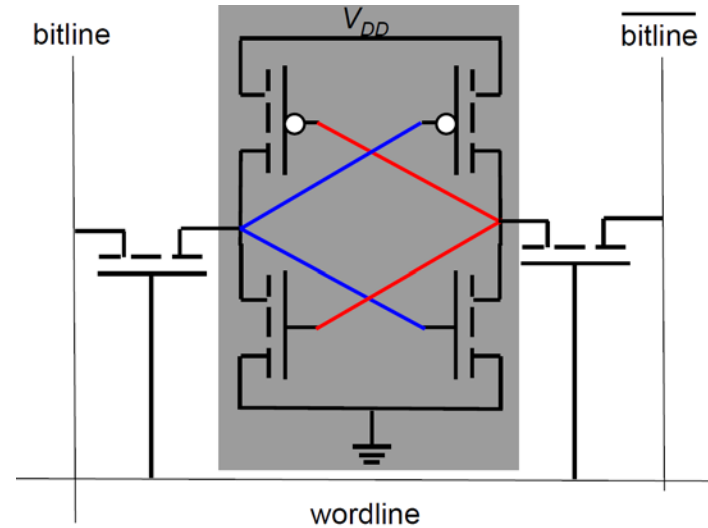
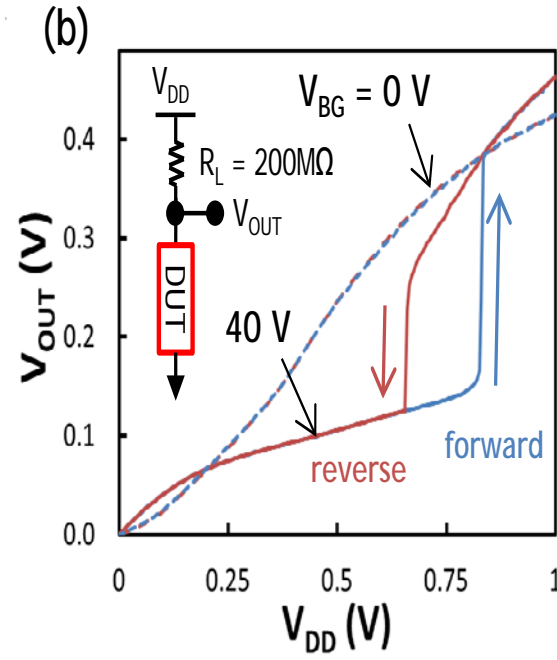
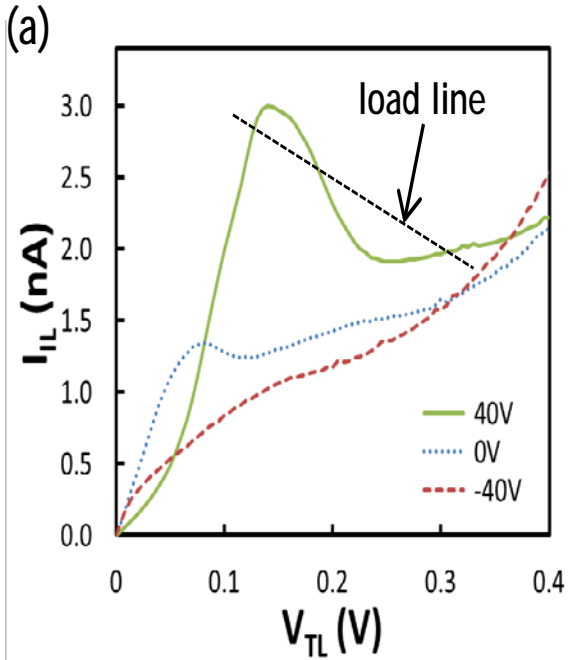


HRTEM AND EELS OF ITFET
(COURTESY, M. KIM)

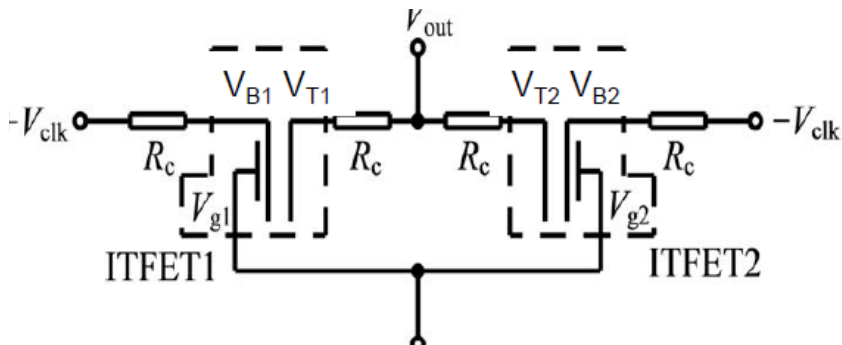
Tunneling vs. Temperature and Magnetic Field



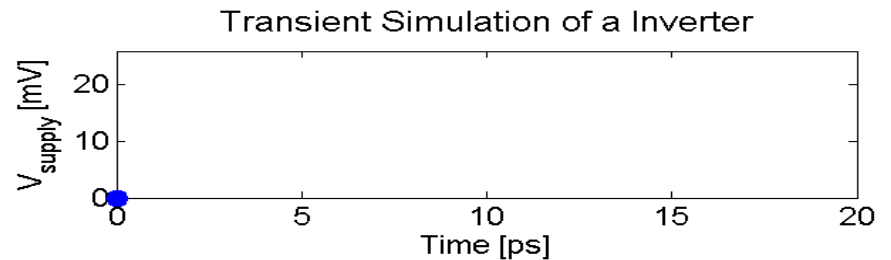
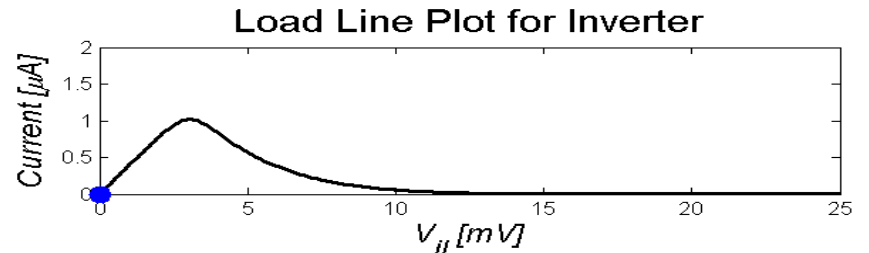
ITFET SRAM and Inverter



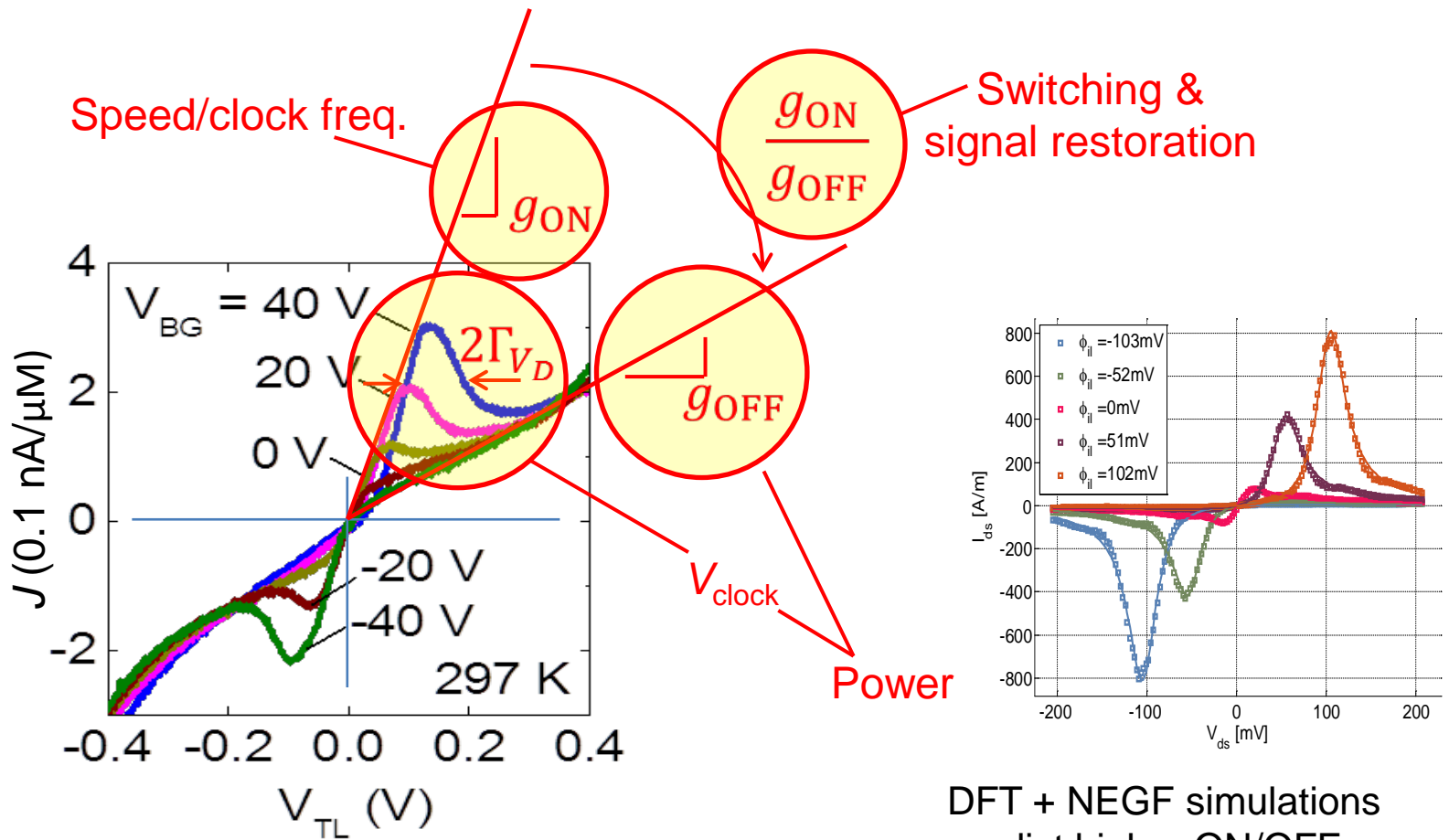
Kang... Register, Tutuc, Banerjee, EDL (2015)



$V_{in} = 0, 1$
 $V_{out} = 1, 0$



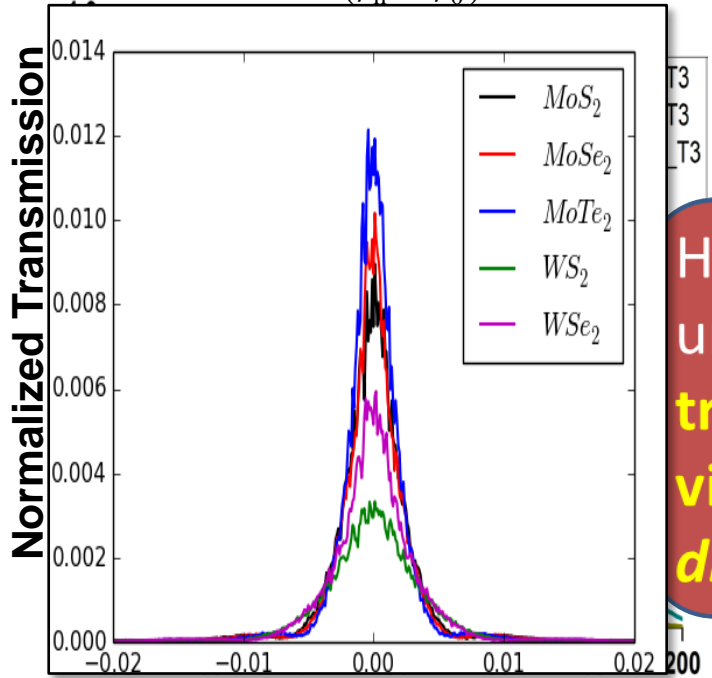
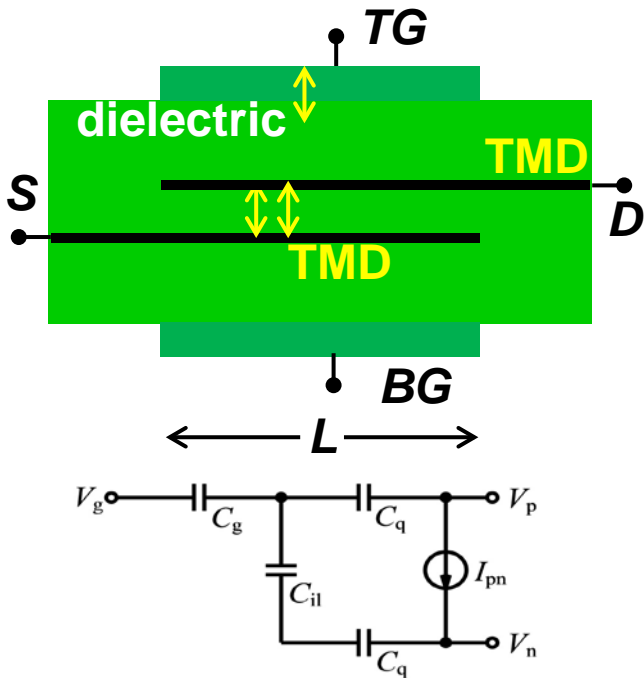
Effects of device characteristics on ITFET circuit performance



DFT + NEGF simulations predict higher ON/OFF
 Need rotational alignment of electrodes and tunnel barrier

Resonance Broadening, Short-Channel Effects, Carrier Velocity, Scattering

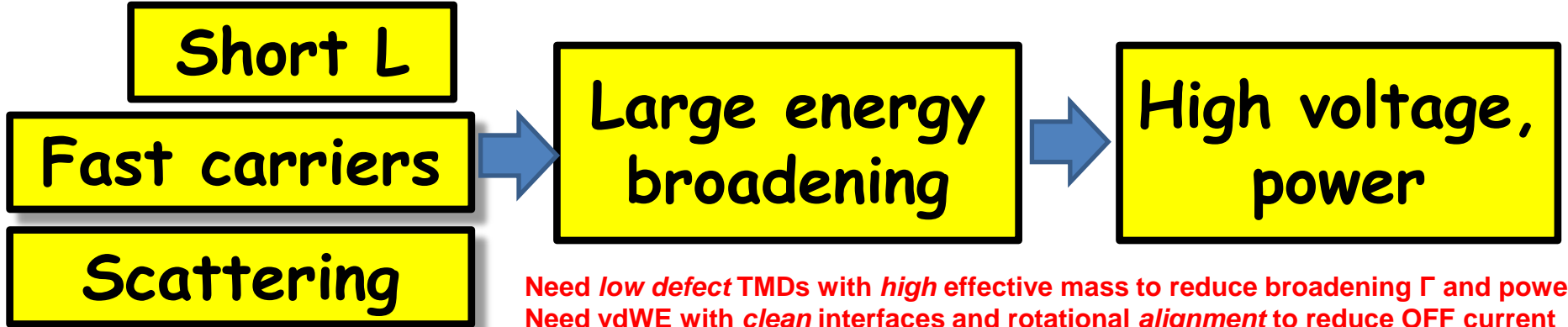
$$I_{\text{tun}} = \frac{A\Gamma(V_p - V_n)}{\Gamma^2 + (\phi_{\text{il}} - \phi_0)^2}$$



Tunneling probability vs. interlayer potential $\pm\Delta V_c$ for 25 meV normally incident electrons in GaAs/AIAs and graphene ITFET

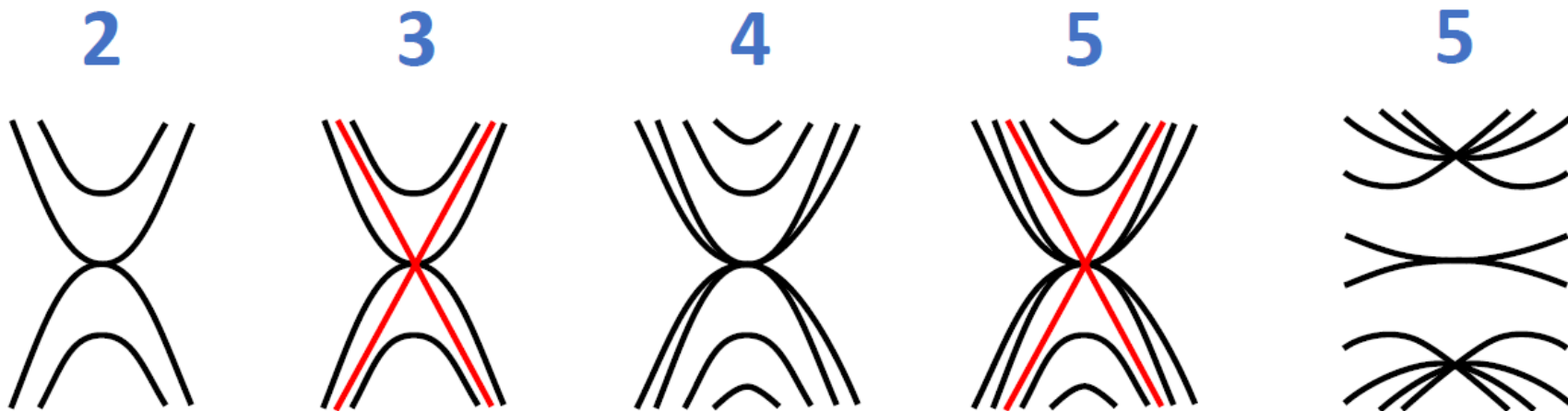
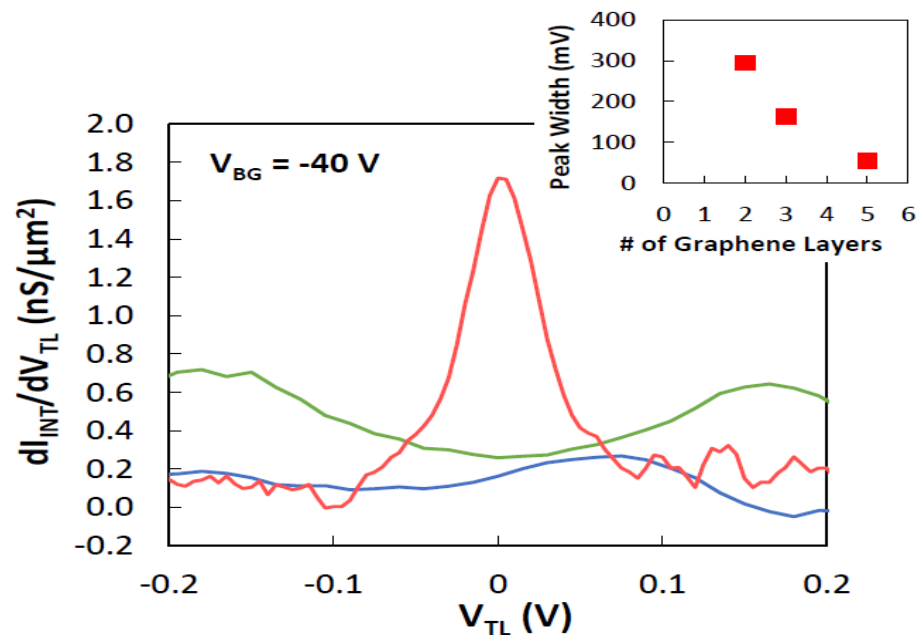
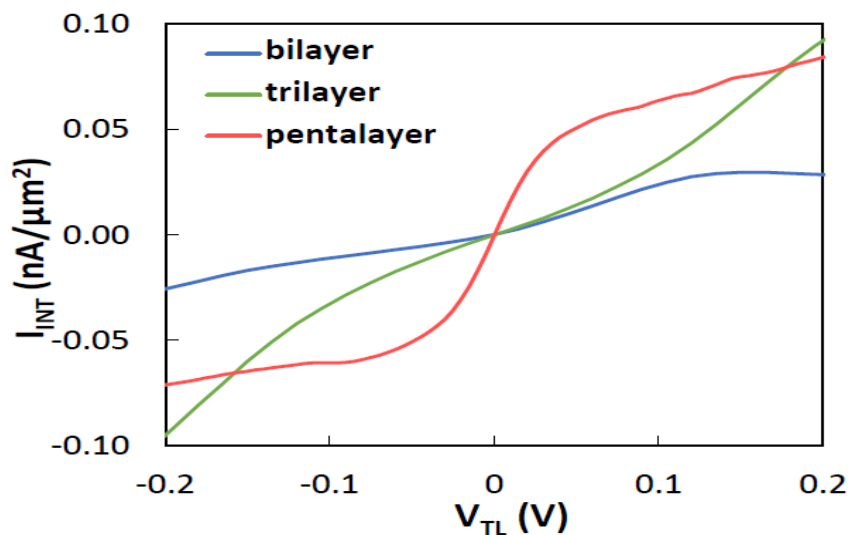
Heisenberg $\Delta k\Delta x$ uncertainty ...
 translated to $\Delta E\Delta x$ via carrier velocity $dE/d(\hbar k)$

Interlayer potential (band edge) difference (meV)



Need *low defect* TMDs with *high* effective mass to reduce broadening Γ and power
 Need vdWE with *clean* interfaces and rotational *alignment* to reduce OFF current

GRAPHENE THICKNESS DEPENDENCE



ABA

ABC

Quantum vs Interlayer Capacitance

$$V_{TL} = \frac{-en_T}{C_{int}} + (\mu_B - \mu_T)/e$$

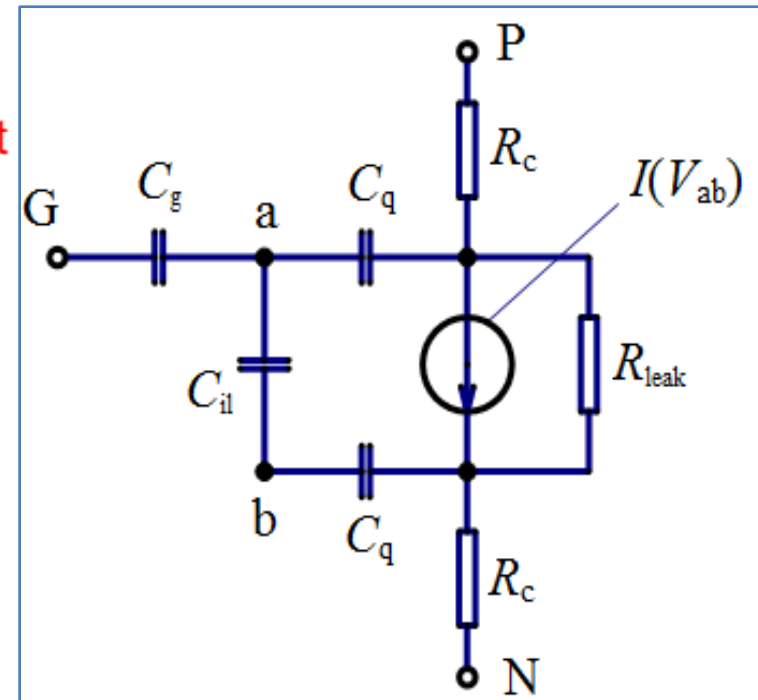
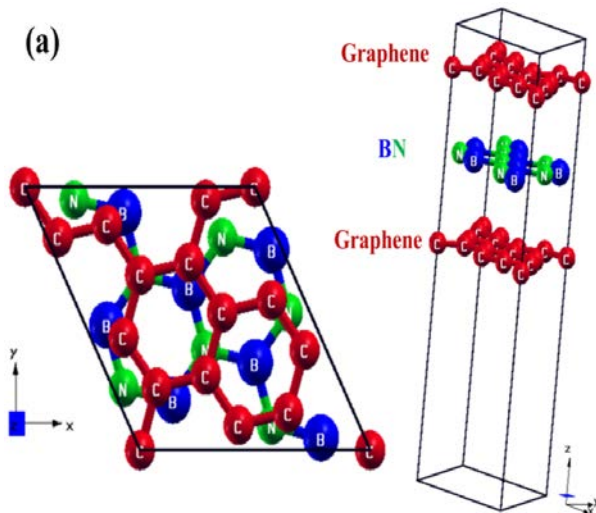
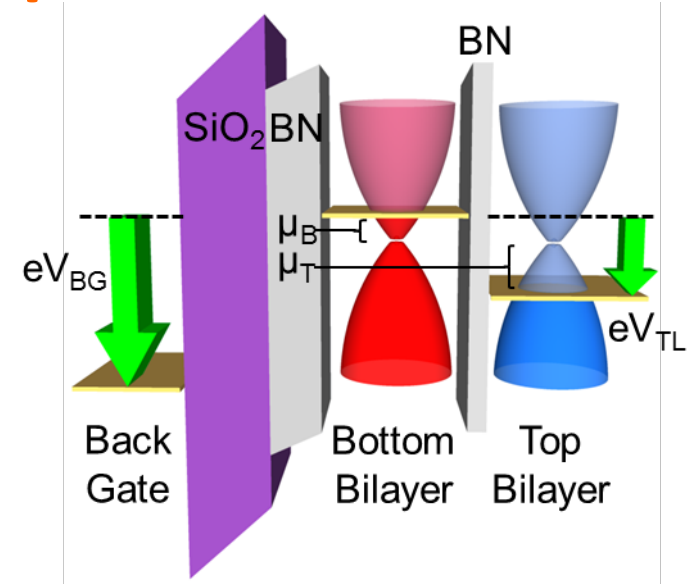
$$V_{ES} = V_{TL} - (\mu_B - \mu_T)/e = 0$$

- Resonances occur when electrons momentum **and** energy are conserved:

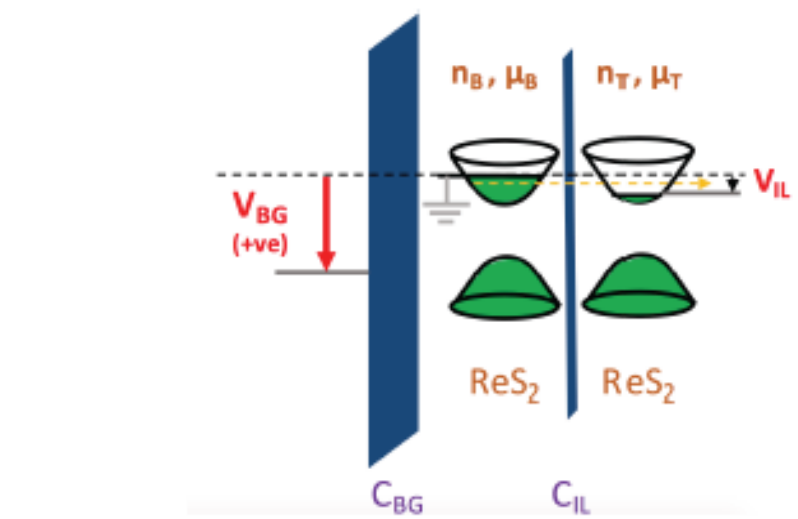
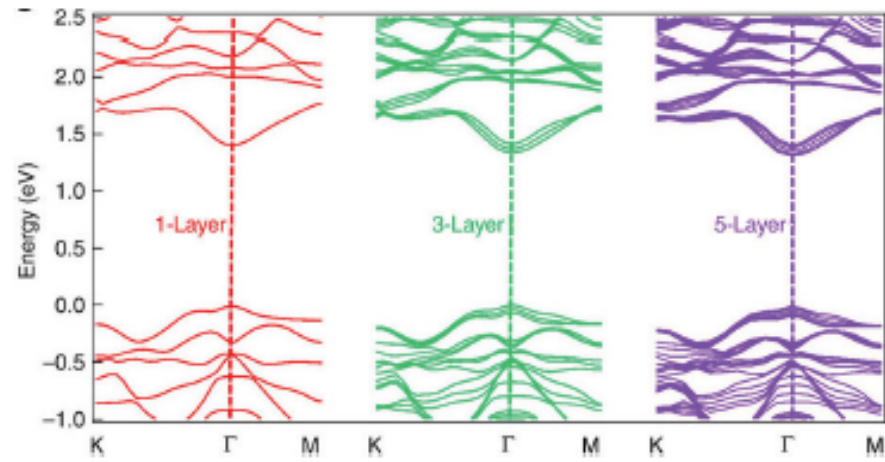
- Using $\mu = \frac{n}{DOS} = \frac{e^2 n}{C_Q}$ $V_{TL} = V_{ES} \left(1 + \frac{2C_{int}}{C_Q} \right)$
- Resonance width Γ "amplified" by $1 + \frac{2C_{int}}{C_Q}$

when measured as a function of V_{TL}

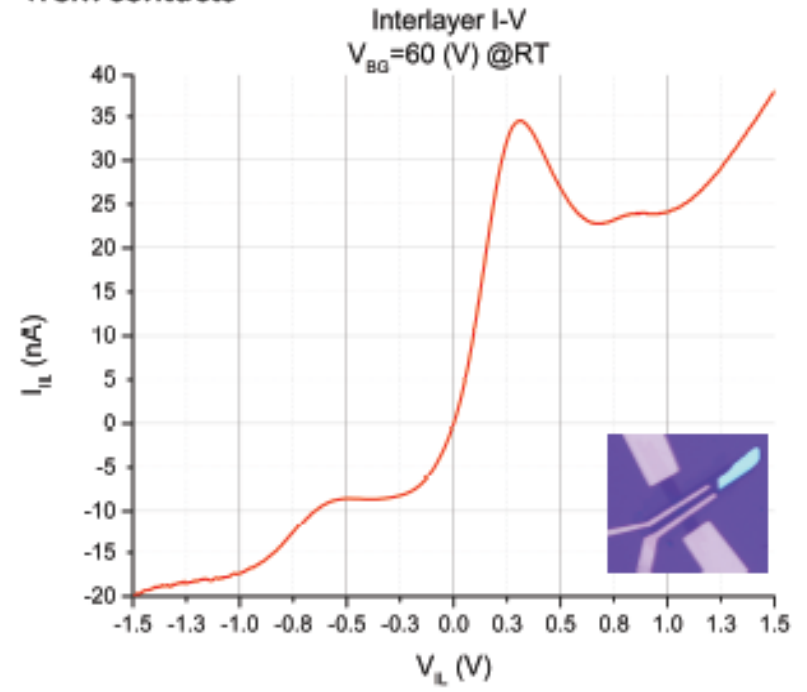
- Intrinsic resonance width (Γ) in V_{ES} determined by quasi-particle lifetime and rotational misalignment



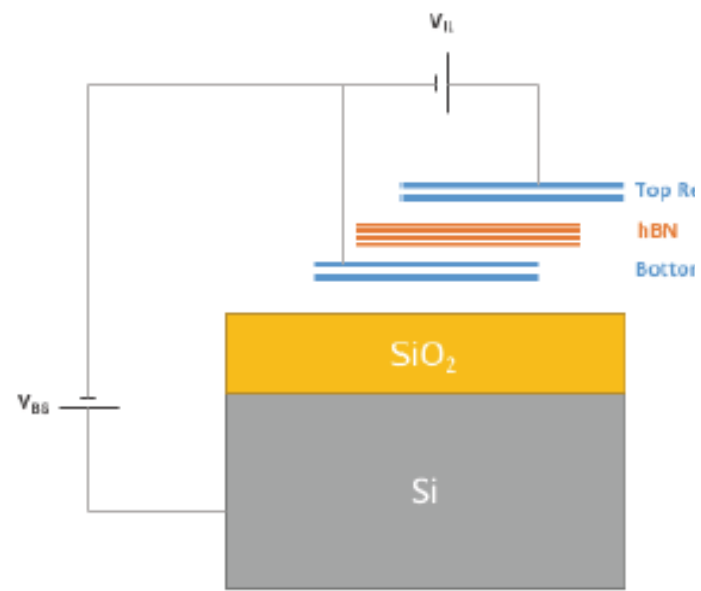
- ReS₂ is a stable, direct bandgap TMD material, regardless of the number of layers [1].
- Ab initio calculations indicate bandgaps of monolayer, tri-layer, and five-layer ReS₂ are 1.44, 1.4, and 1.35 eV, respectively [1].



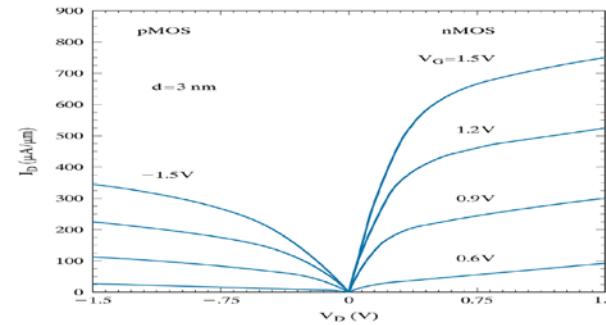
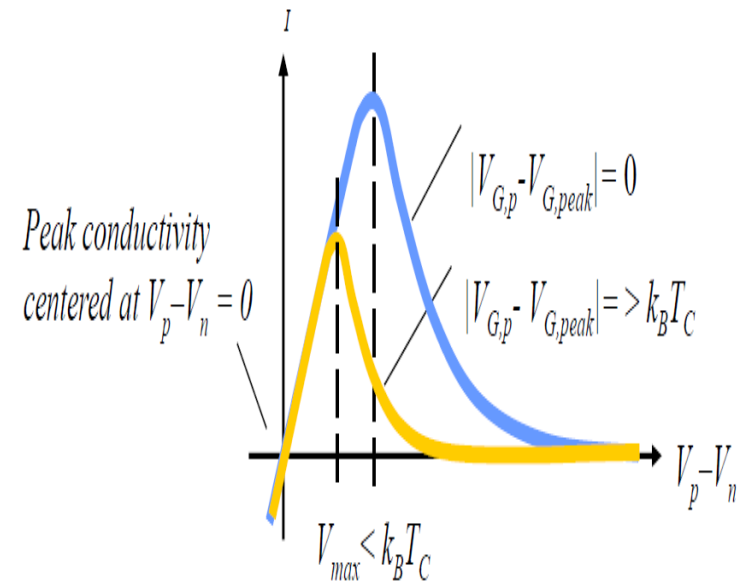
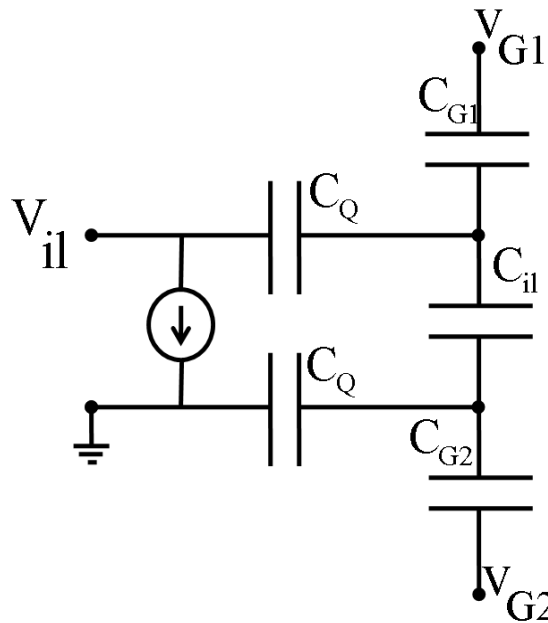
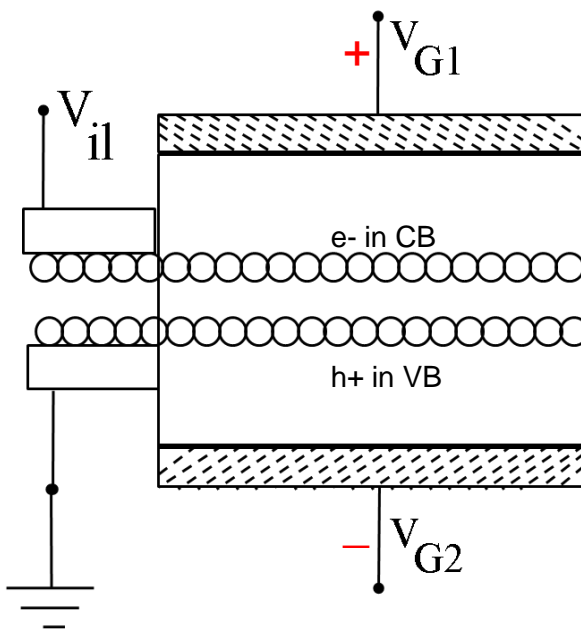
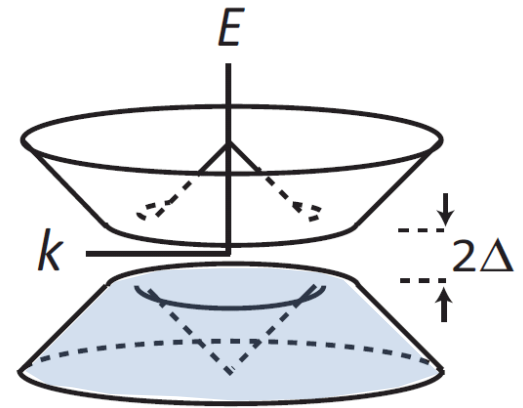
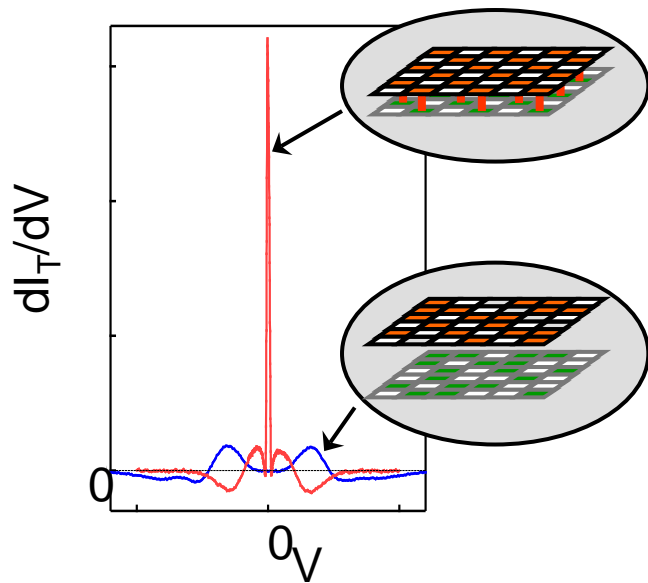
- Room temperature interlayer I-V characteristics showing multiple NDR. However, there could also be contribution from contacts



- Schematic and biasing scheme of the device; the n⁺ Si substrate is used as the back gate while the top layer is biased and the bottom layer is at ground.

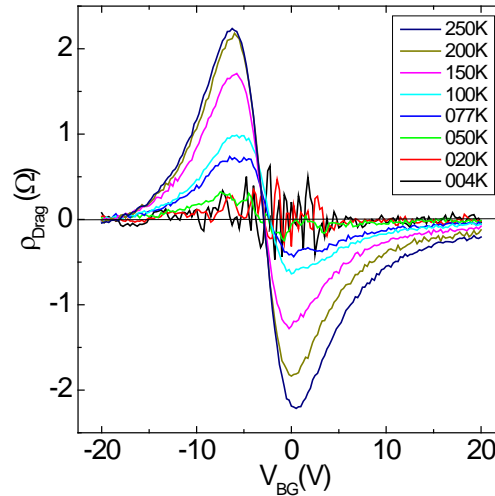
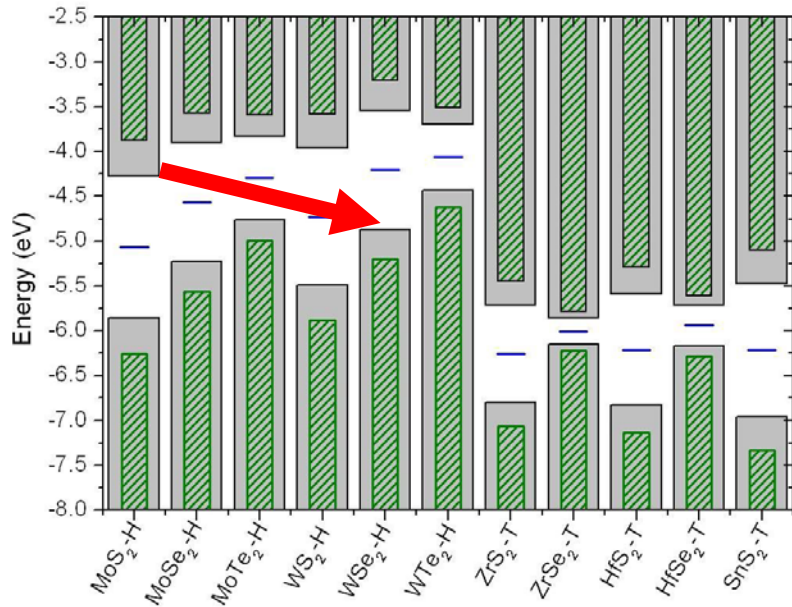
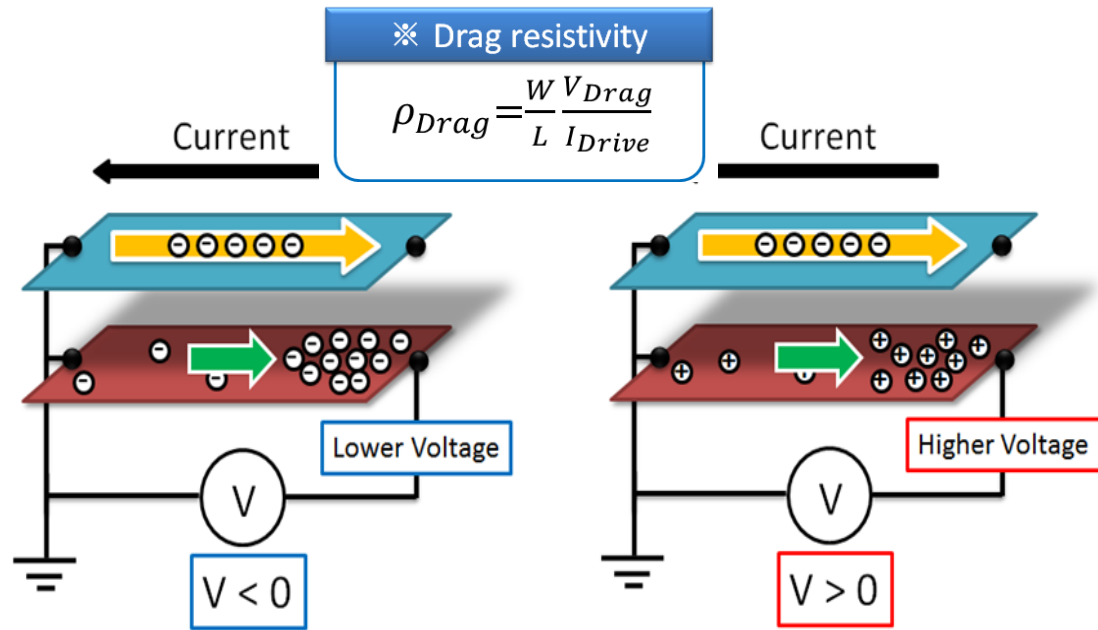
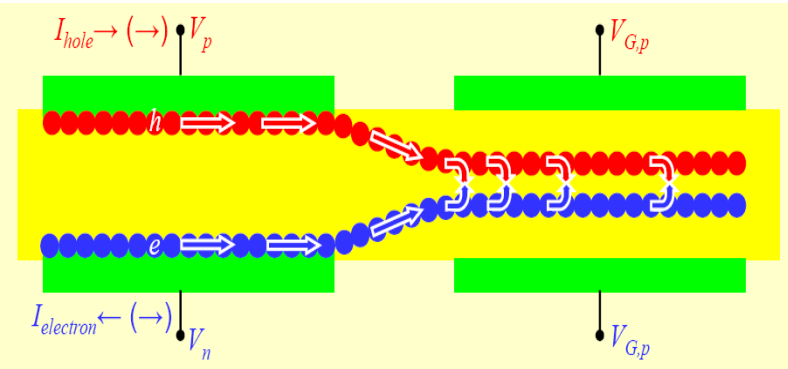


Bi-layer pseudoSpin Field Effect Transistor (BiSFET)

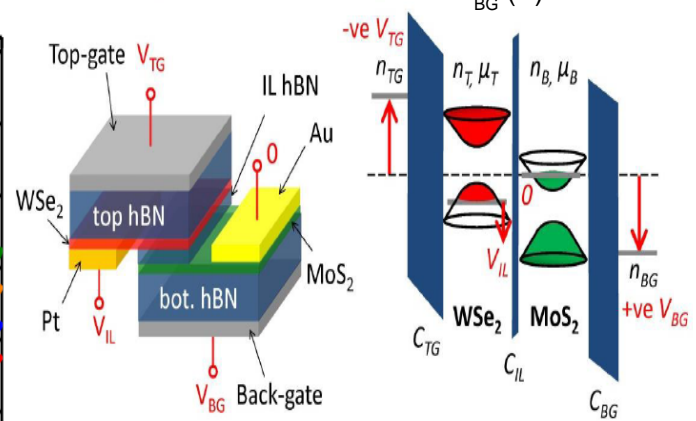
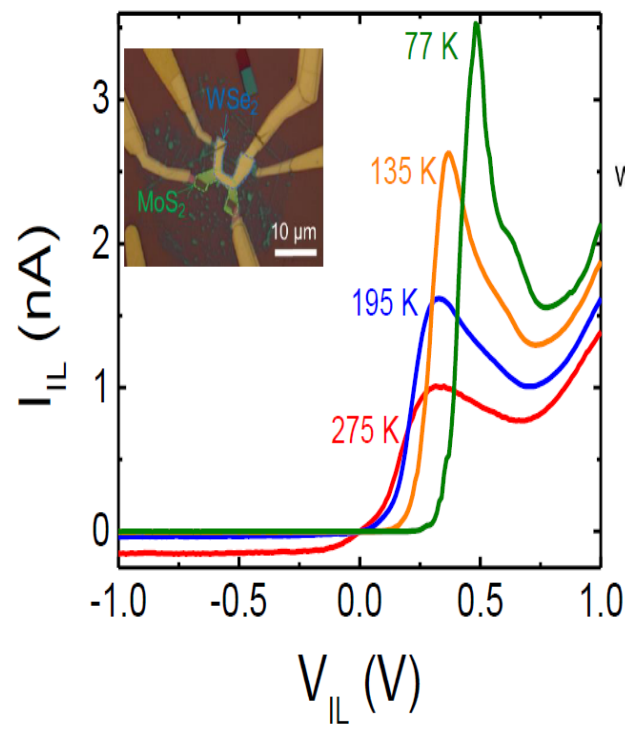
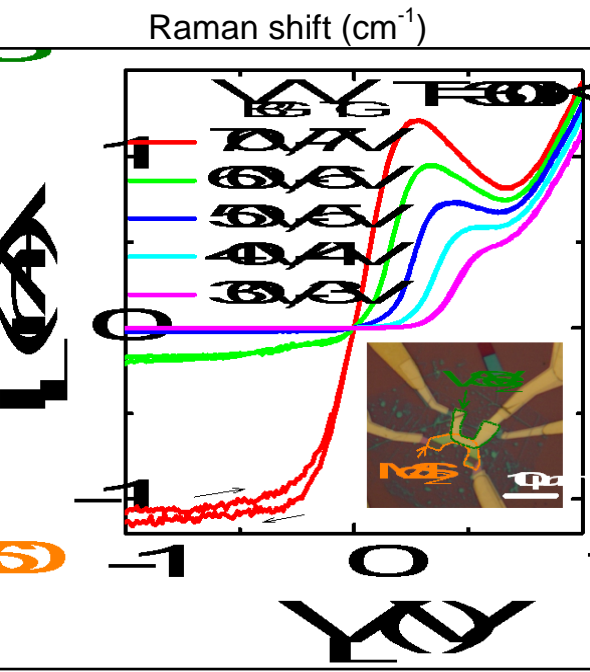
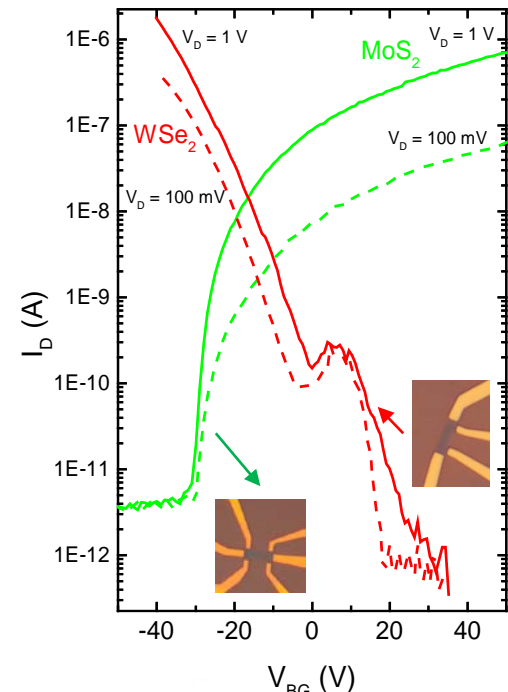
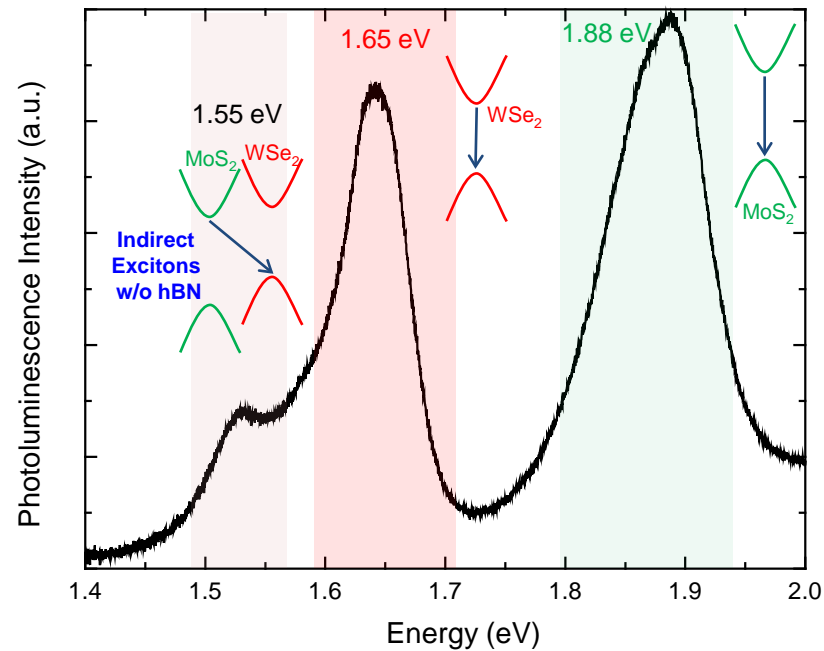
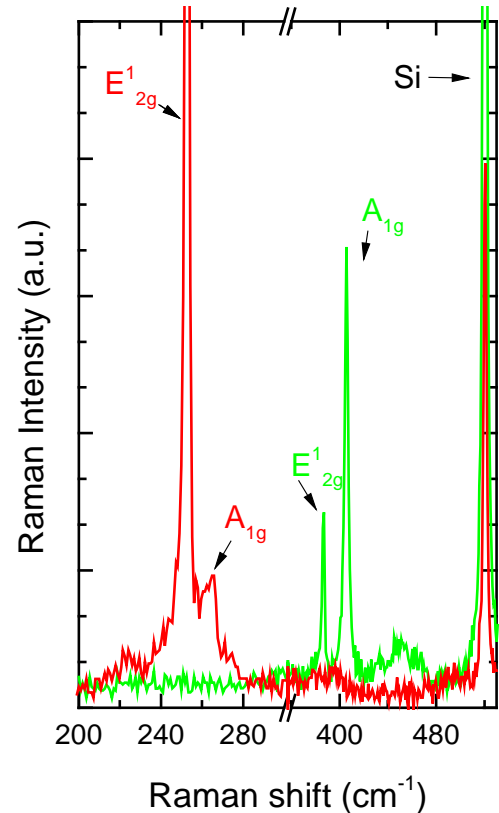


“Bi-layer pseudoSpin Field Effect Transistor (BiSFET): a proposed new logic device”
 Banerjee, Register, Tutuc, Reddy and Macdonald, IEEE EDL, Feb. 2009; also US patent

Bose Condensate in Graphene/TMD Heterostructures??



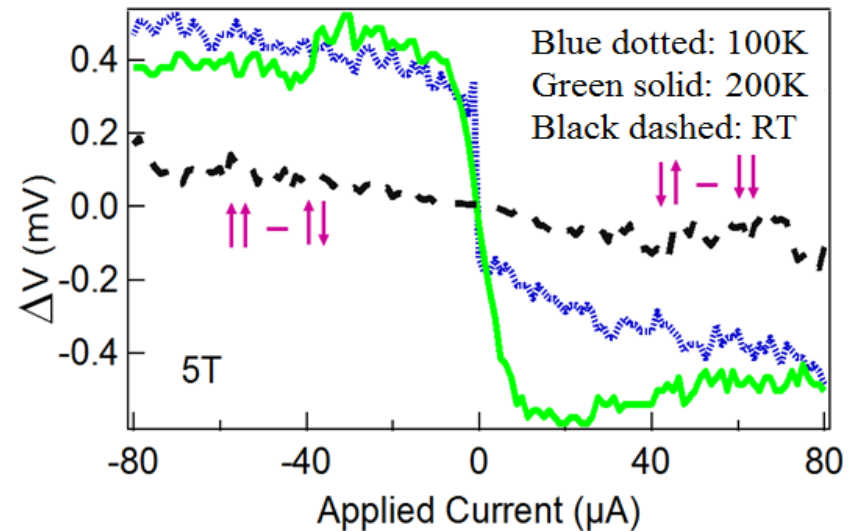
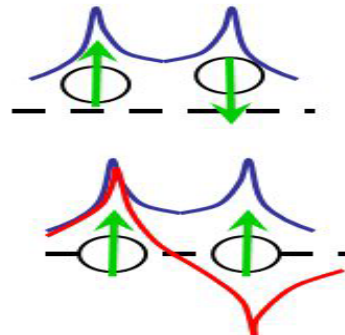
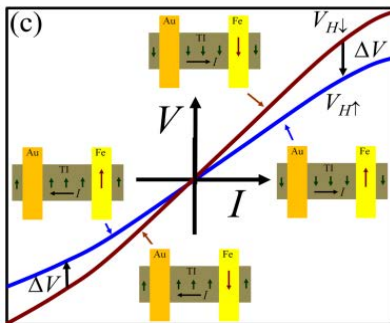
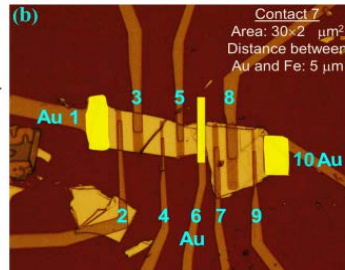
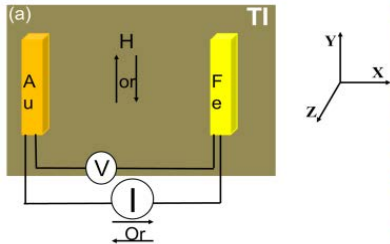
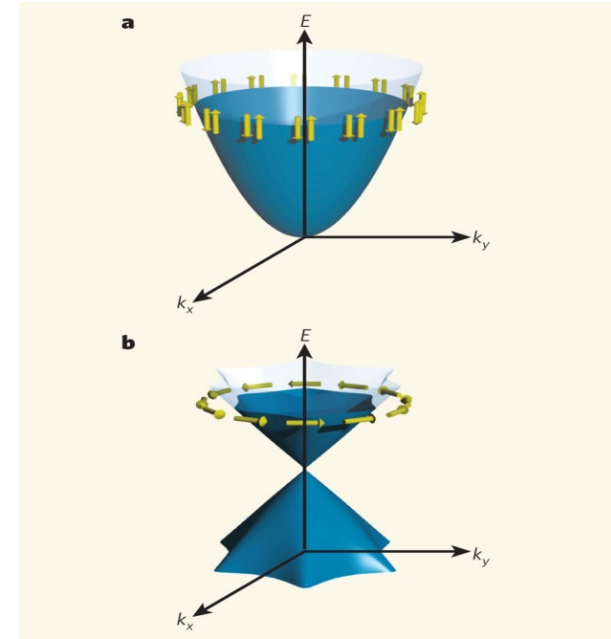
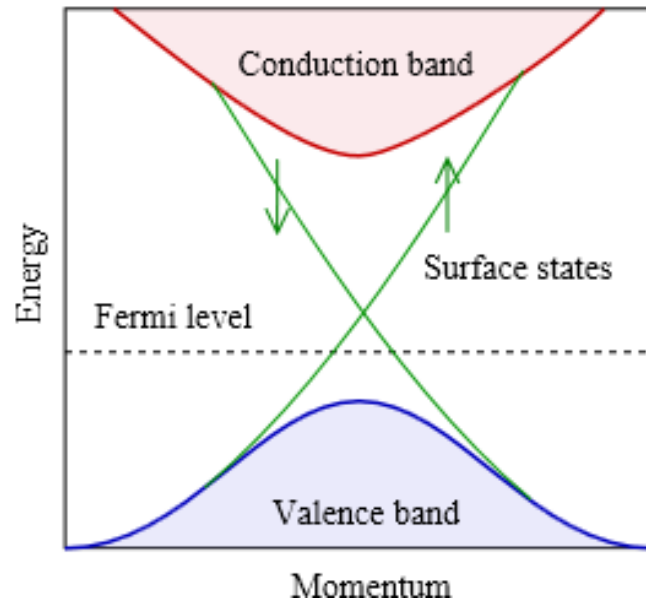
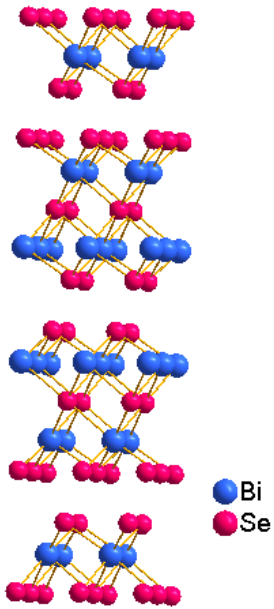
$$\frac{1}{\tau(\mathbf{k}_1)} \propto \sum_{\mathbf{k}'_1 \mathbf{k}_2 \mathbf{k}'_2} |W|^2 f_1 f_2 (1 - f_1') (1 - f_2') \delta(\epsilon_1 + \epsilon_2 - \epsilon_1' - \epsilon_2') \delta_{\mathbf{k}_1 + \mathbf{k}_2, \mathbf{k}'_1 + \mathbf{k}'_2}$$



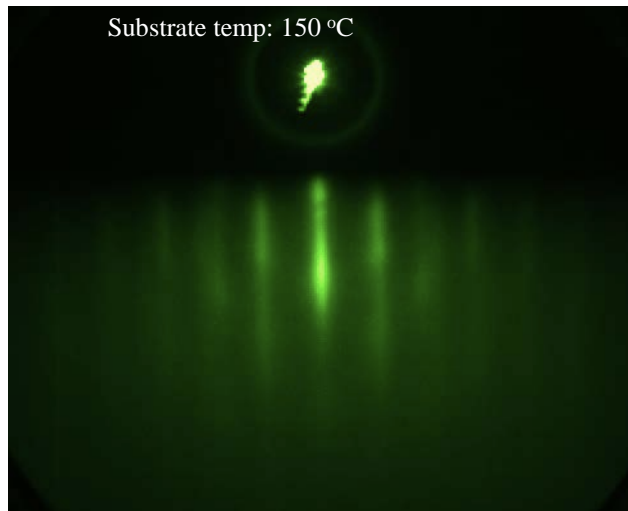
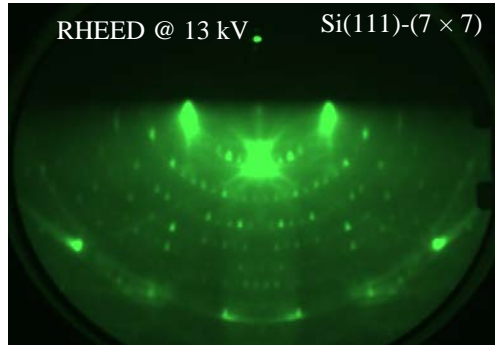
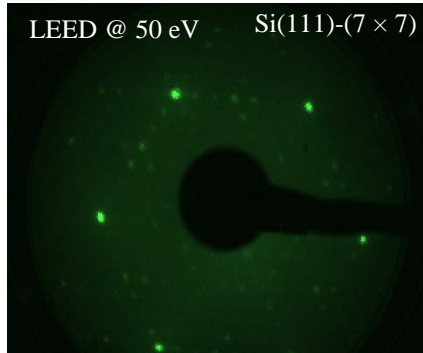
$$eV_{BG} = \frac{e^2 n_{BG}}{C_{BG}} + \mu_B \quad (1) \quad eV_{TG} = \frac{e^2 n_{TG}}{C_{TG}} + \mu_T + eV_{IL} \quad (2)$$

$$eV_{IL} = \frac{e^2 (n_T + n_{TG})}{C_{IL}} + \mu_B - \mu_T \quad (3) \quad n_{T(B)} = f(\mu_{T(B)}) \quad (4)$$

Spintronics with Topological Insulators

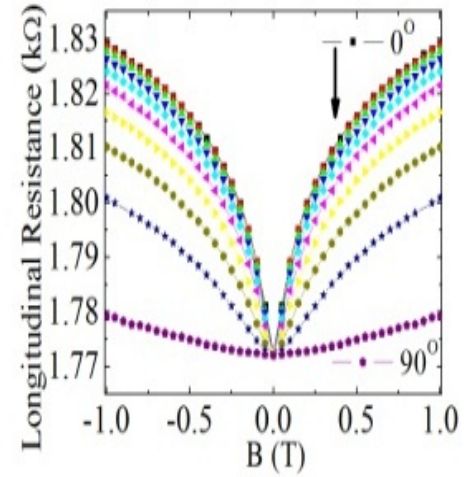
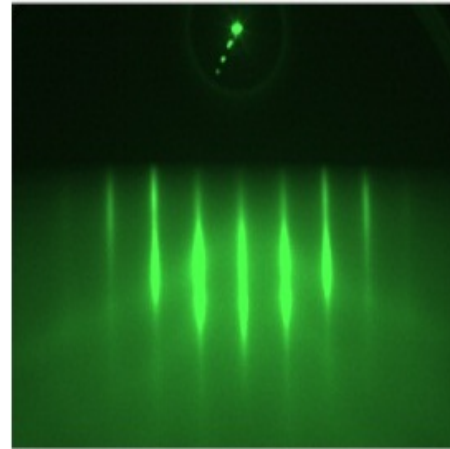


MBE of topological insulators

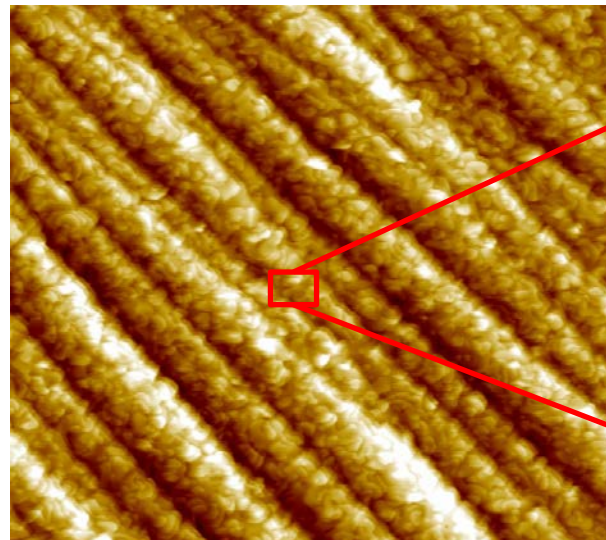


Sharp RHEED streaks

Bi₂Te₃ on Si(111)

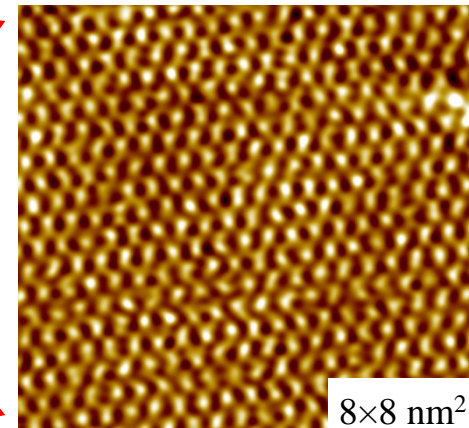


Bi₂Se₃ on Si(111)



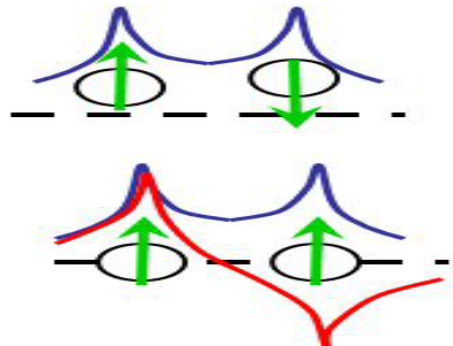
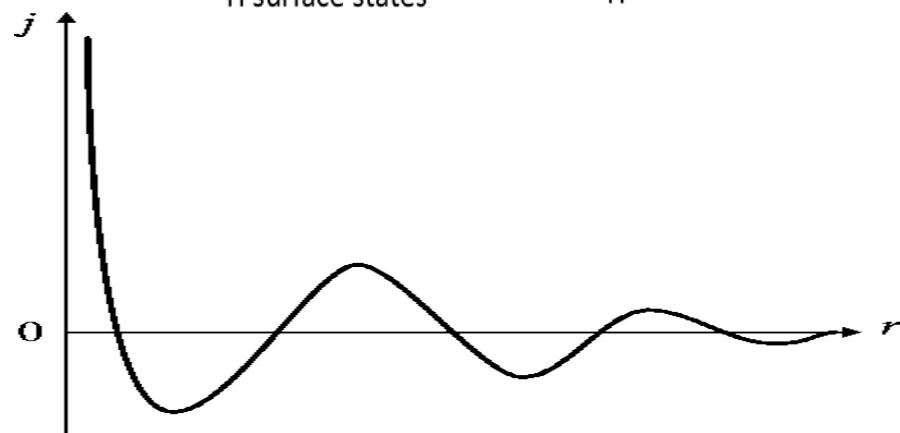
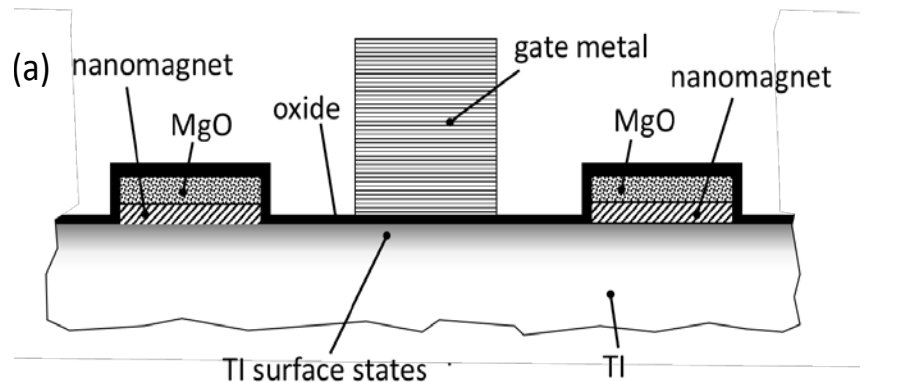
STM at -2 V, 1 nA

1000x1000 nm²



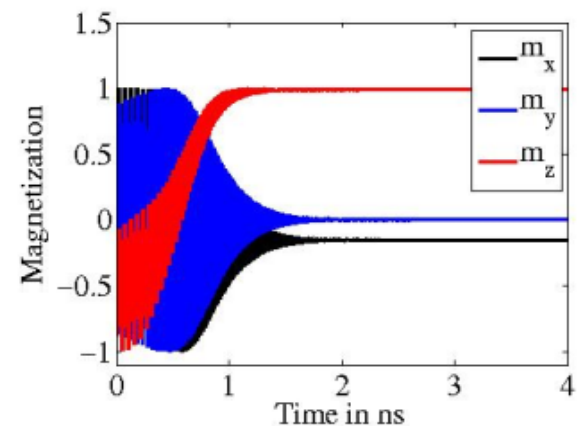
8 × 8 nm²

RKKY Coupling of Nanomagnets on TI



$$H^{\text{RKKY}} = -\frac{J^2 \epsilon_F}{2\pi^2 \hbar^2 v_F^2 R^2} \left[(S_1^x S_2^x + S_1^z S_2^z) \sin\left(\frac{2R\epsilon_F}{\hbar v_F}\right) - (\mathbf{S}_1 \times \mathbf{S}_2)_y \cos\left(\frac{2R\epsilon_F}{\hbar v_F}\right) \right]$$

$$\frac{d\hat{\mathbf{m}}}{dt} = -\gamma(\hat{\mathbf{m}} \times \mathbf{H}_{\text{eff}}) + \alpha \left(\hat{\mathbf{m}} \times \frac{d\hat{\mathbf{m}}}{dt} \right)$$



$$\Delta = V[K_u - 0.5 \mu_0 M_S^2 (N_{zz} - N_{xx})]$$

$$\tau = \tau_0 e^{\Delta/k_B T}$$

$$E_S = C_g V_g^2$$

Sub aJ energies possible

Ghosh, Register, Banerjee, JAP 2016;
patent disclosure

Epilog

- Need advances in vdW epitaxy of heterostructures, and in process modules such as doping and contacts
- Negative differential resistance (NDR) Tunnel FETs can lead to novel logic and memory
- Pseudospintronics and spintronics for ultra-power and non-volatile devices
- IoT devices need on chip power generation